

Polarized Electron Sources @ JLAB

WebPage - www.jlab.org/accel/inj_group

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- Alicia Hofler (Old Dominion University, JLab staff)

Source Group “Hall of Famers” - Charlie Sinclair, Bruce Dunham, *Larry Cardman*, Scott Price, Peter Hartmann, Michael Steigerwald, Tony Day, *Kim Ryan*, *Danny Machie*, John Hogan, Bill Schneider, *Reza Kazimi*, Paul Rutt, *Ganapati Rao Myneni*

JLab Summer Science Series
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Thomas Jefferson National Accelerator Facility

A history 30+ years and growing...

Polarized electron beams have wide application in studies which range from materials science to nuclear and high energy physics:

⇒ the latter has driven the development of polarized e- sources

Semiconductor sources introduced in 1975 via optical pumping of GaAs

First e- source on an accelerator (P ~ 35%) : PEGGY, at SLAC (1978)

Strained GaAs reaches higher polarization (P~75%) in early 90's (SLAC)

Strained Superlattice GaAs even higher (P~85%) last few years (SLAC)

Many accelerator facilities have had polarized e- GaAs sources:

CEBAF, MAMI, Bonn, SLAC, MIT-BATES

1980 ~ 1 microAmp 2000 ~ 100 microAmp 2010 ~ milliAmp ??



Gallium Arsenide

3" wafer cleaved into square photocathodes (15.5 mm) for mounting on a "stalk" using In and Ta cup.

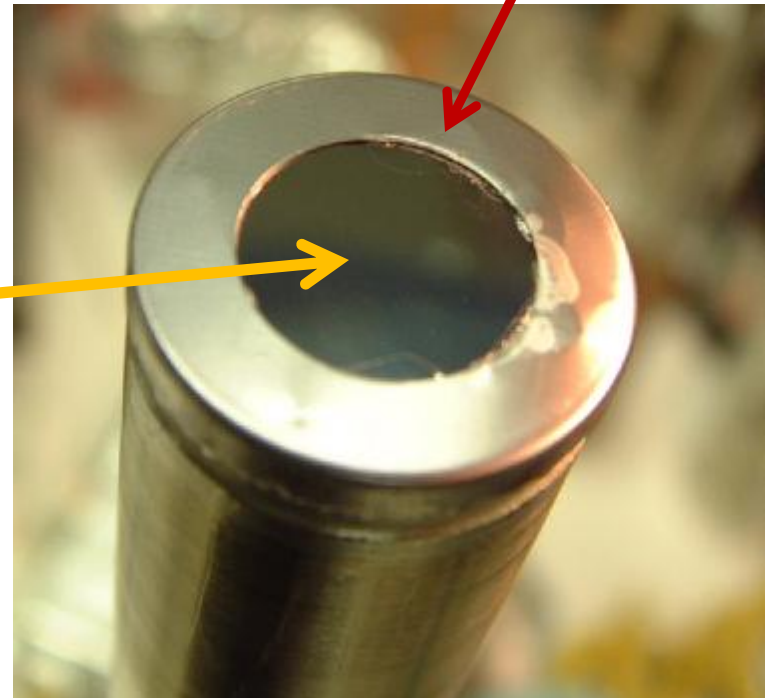
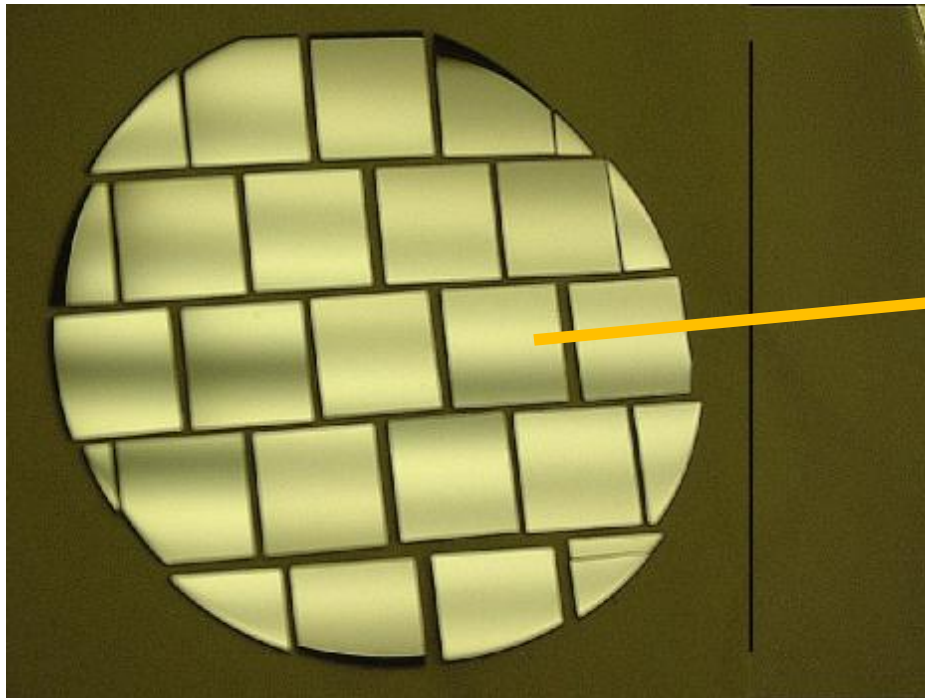
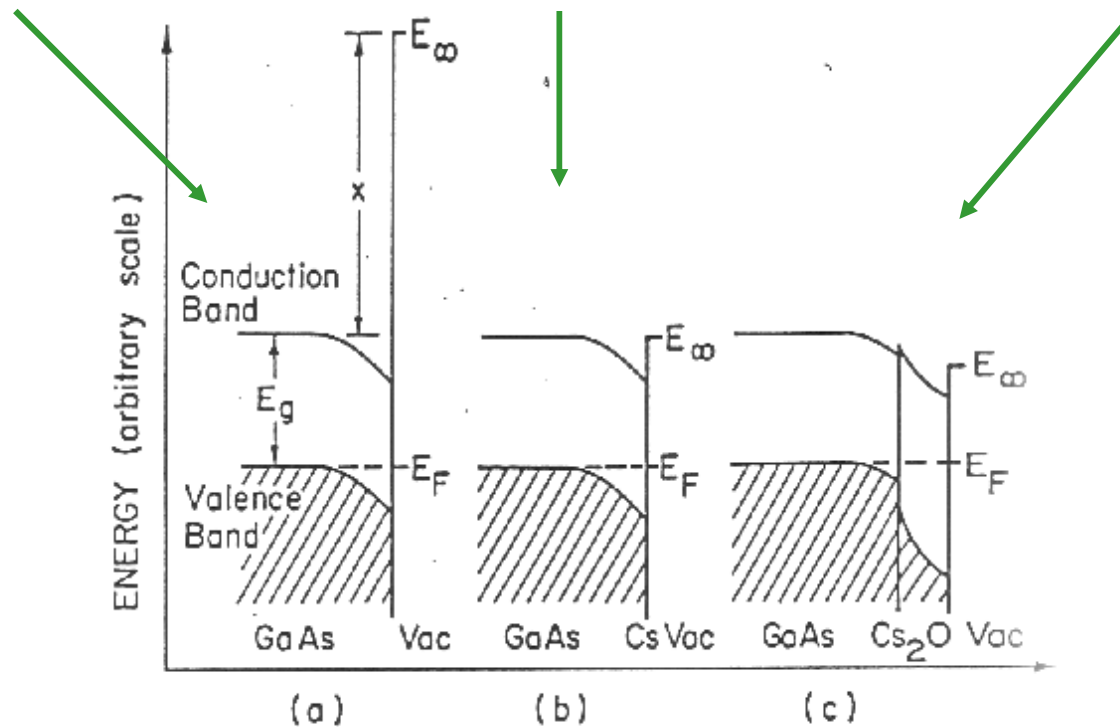


Photo-Emission from GaAs

Bare GaAs surface;
Large work function.
No electrons

Alkali (Cs) reduces
work function.
Some electrons.

Cesium + Oxidant (O or NF₃)
"Negative Electron Affinity".
Many electrons



$$QE = \frac{\# e^-s}{\# \gamma's}$$

$$E_a > 0$$

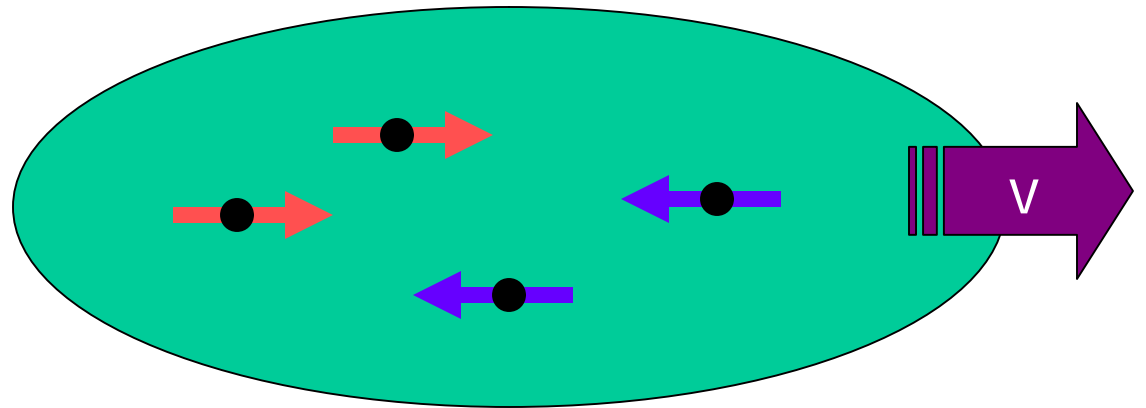
$$E_a \approx 0$$

$$E_a < 0$$

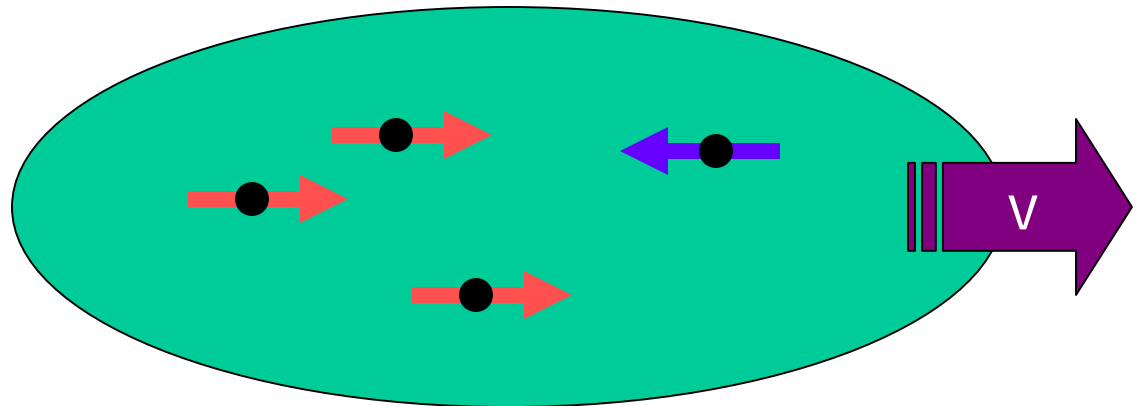


Electron Spin & Polarization

0% Polarization

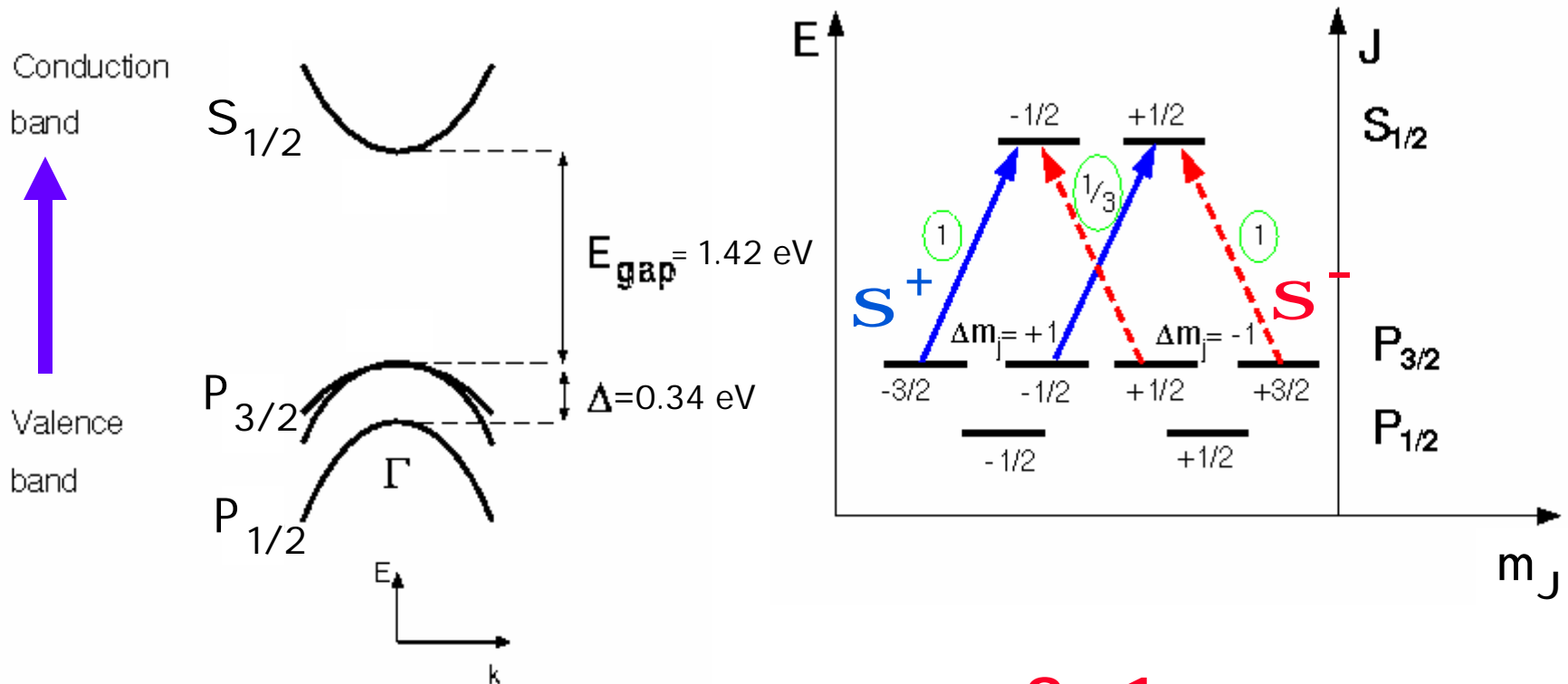


50% Polarization



Aligning the Spin States in GaAs

Optical pumping between $P_{3/2}$ and $S_{1/2}$



$$E_{\text{gap}} < E_g < E_{\text{gap}+D}$$

$$\uparrow$$

$$hc / \lambda$$

$$P_e = \frac{3-1}{3+1} = +/- 50\%$$



The First GaAs Photoemission Gun

PHYSICAL REVIEW B

VOLUME 13, NUMBER 12

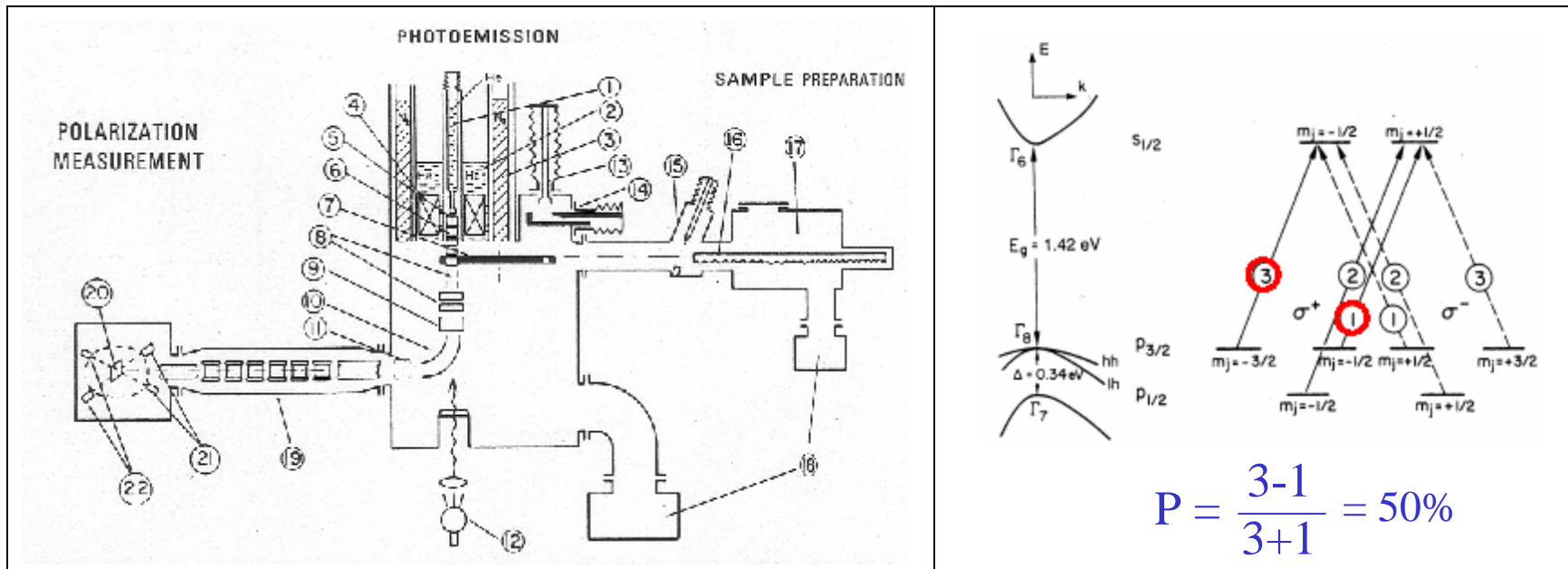
15 JUNE 1976

Photoemission of spin-polarized electrons from GaAs

Daniel T. Pierce* and Felix Meier

Laboratorium für Festkörperphysik, Eidgenössische Technische Hochschule, CH 8049, Zürich, Switzerland

(Received 10 February 1976)

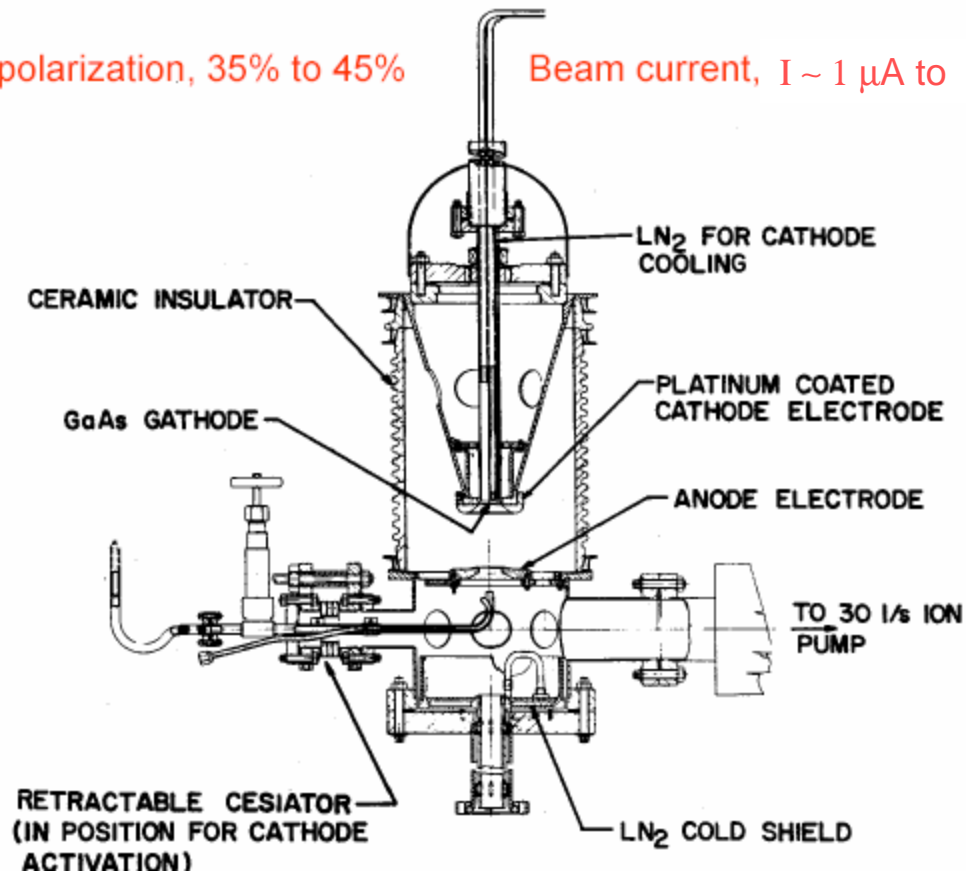


First High Voltage GaAs Photogun

Polarized e⁻ Gun for SLAC Parity Violation Experiment

Beam polarization, 35% to 45%

Beam current, $I \sim 1 \mu\text{A}$ to 15 A peak



Electrons into the accelerator Dec., 1977

Collaboration announces parity violation June, 1978

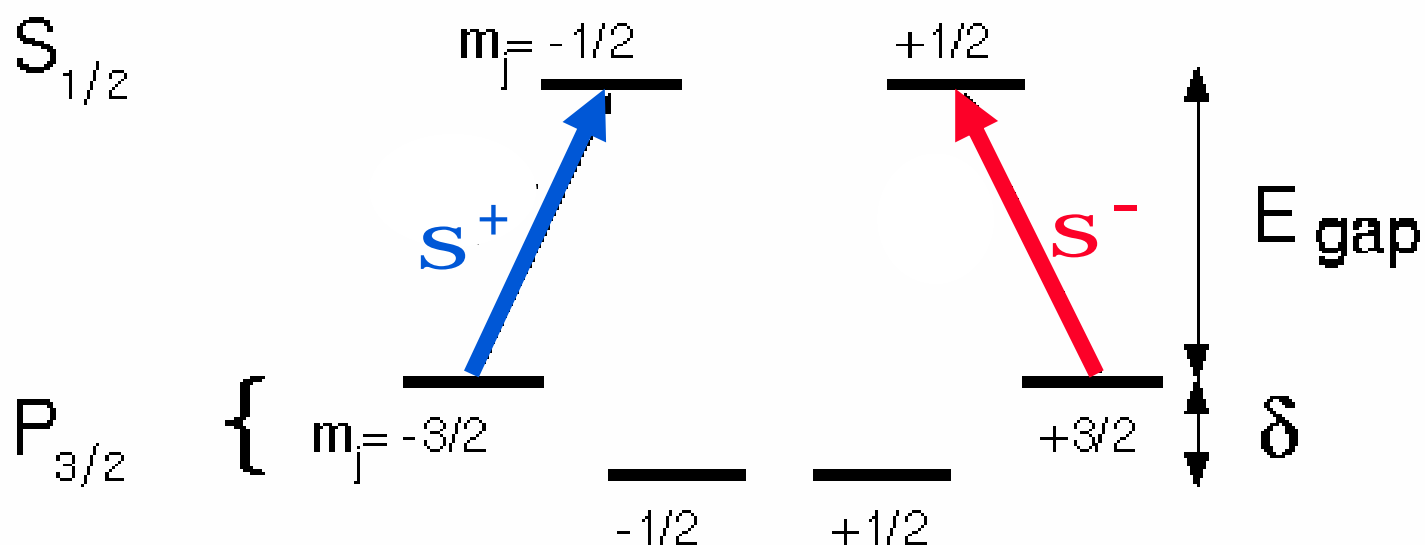


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Breaking the degeneracy ...

Split degeneracy of $P_{3/2}$

& optical pumping between $P_{3/2}$ and $S_{1/2}$



$P_e = +/- 100\%$, with $E_{\text{gap}} < E_g < E_{\text{gap}+d}$



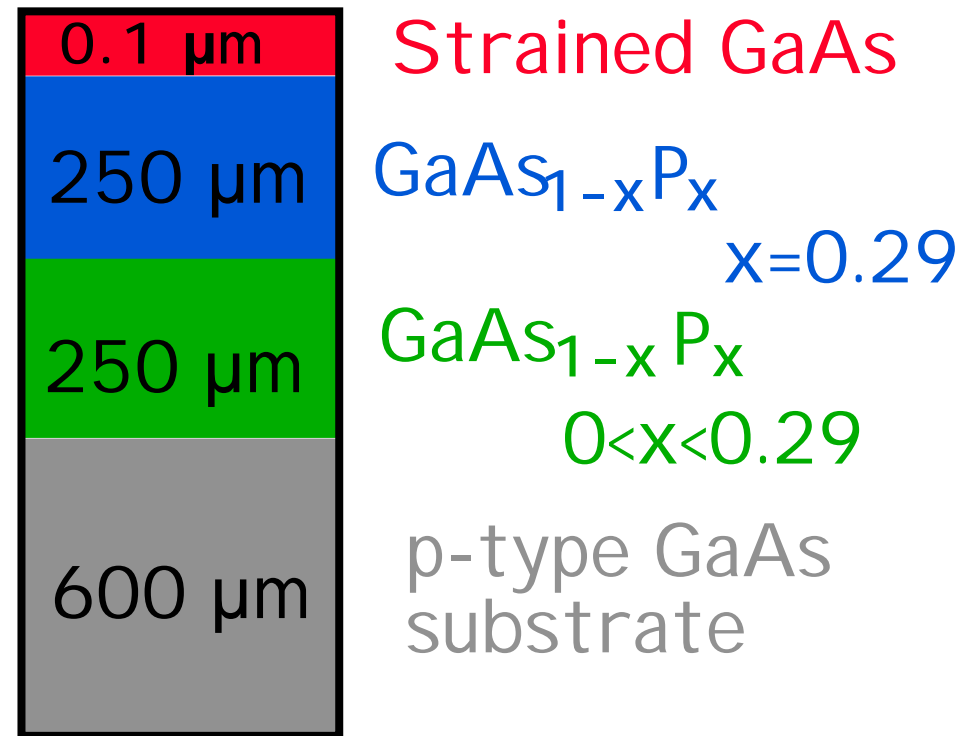
Strained layer GaAs

Bandwidth Semiconductor (formerly *SPIRE*)

- MOCVD-grown epitaxial spin-polarizer wafer

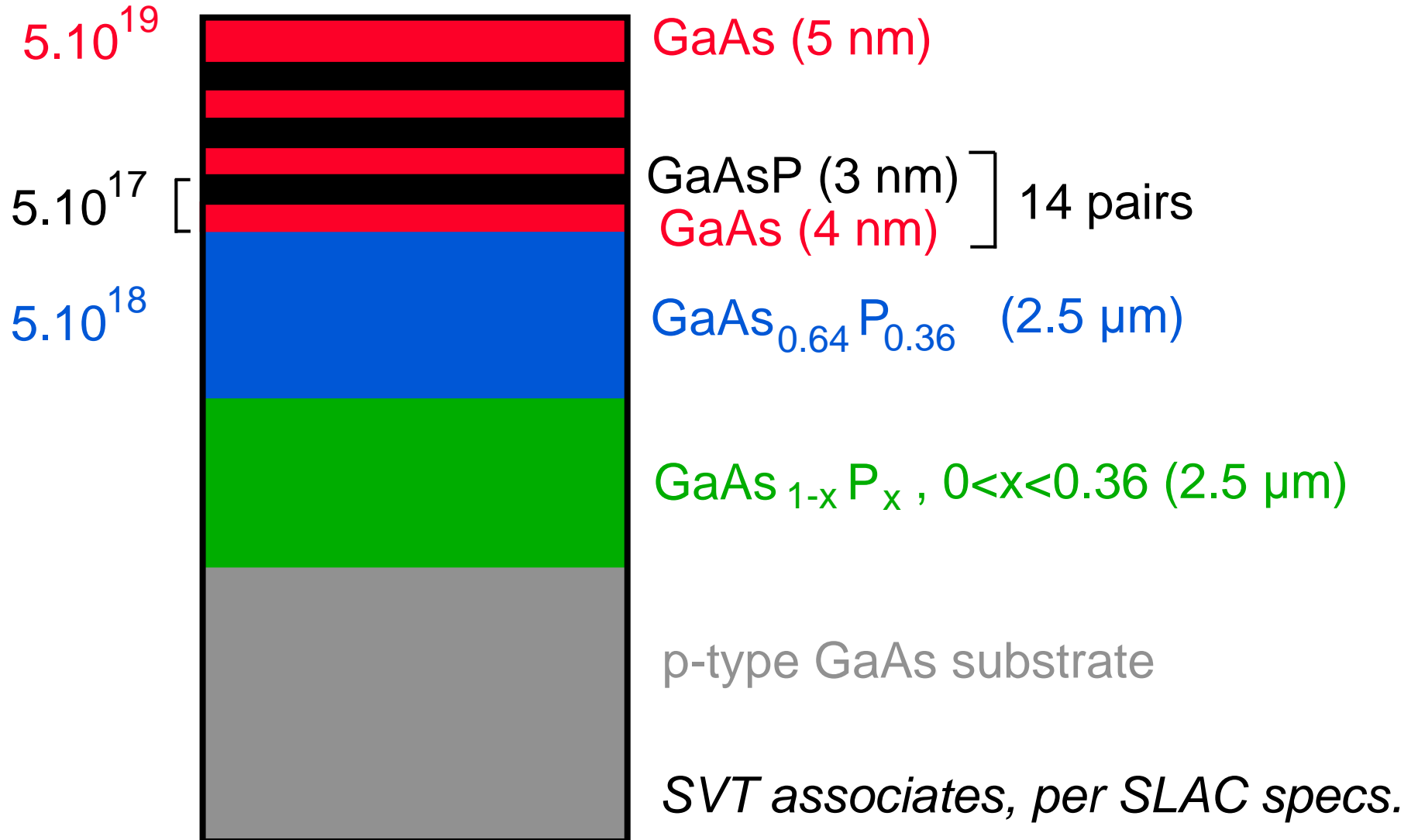
- Lattice mismatch

⇒ split
degeneracy of $P_{3/2}$



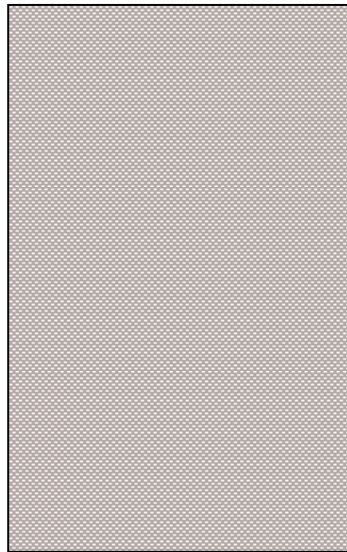
Strained Layer - Superlattice GaAs

Be doping (cm^{-3})



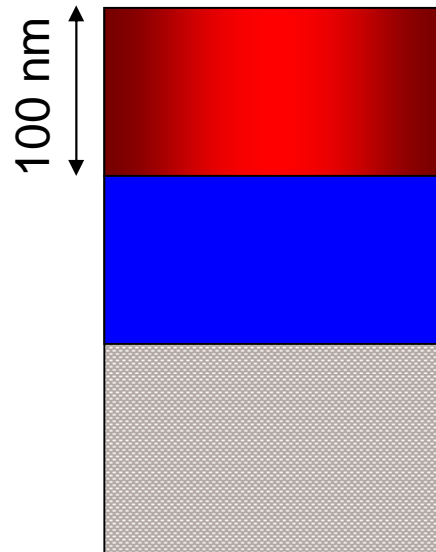
Photocathode Material

Bulk GaAs



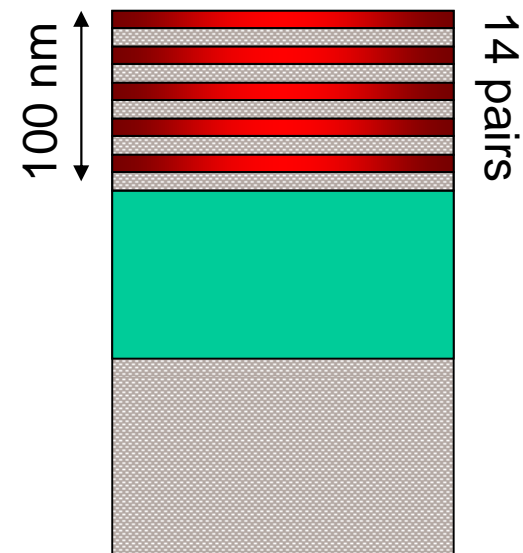
High QE ~ 20%
Pol ~ 35%

Strained GaAs:
GaAs on GaAsP



"conventional" material
QE ~ 0.2%
Pol ~ 75%
@ 850 nm

Superlattice GaAs:
Layers of GaAs on GaAsP

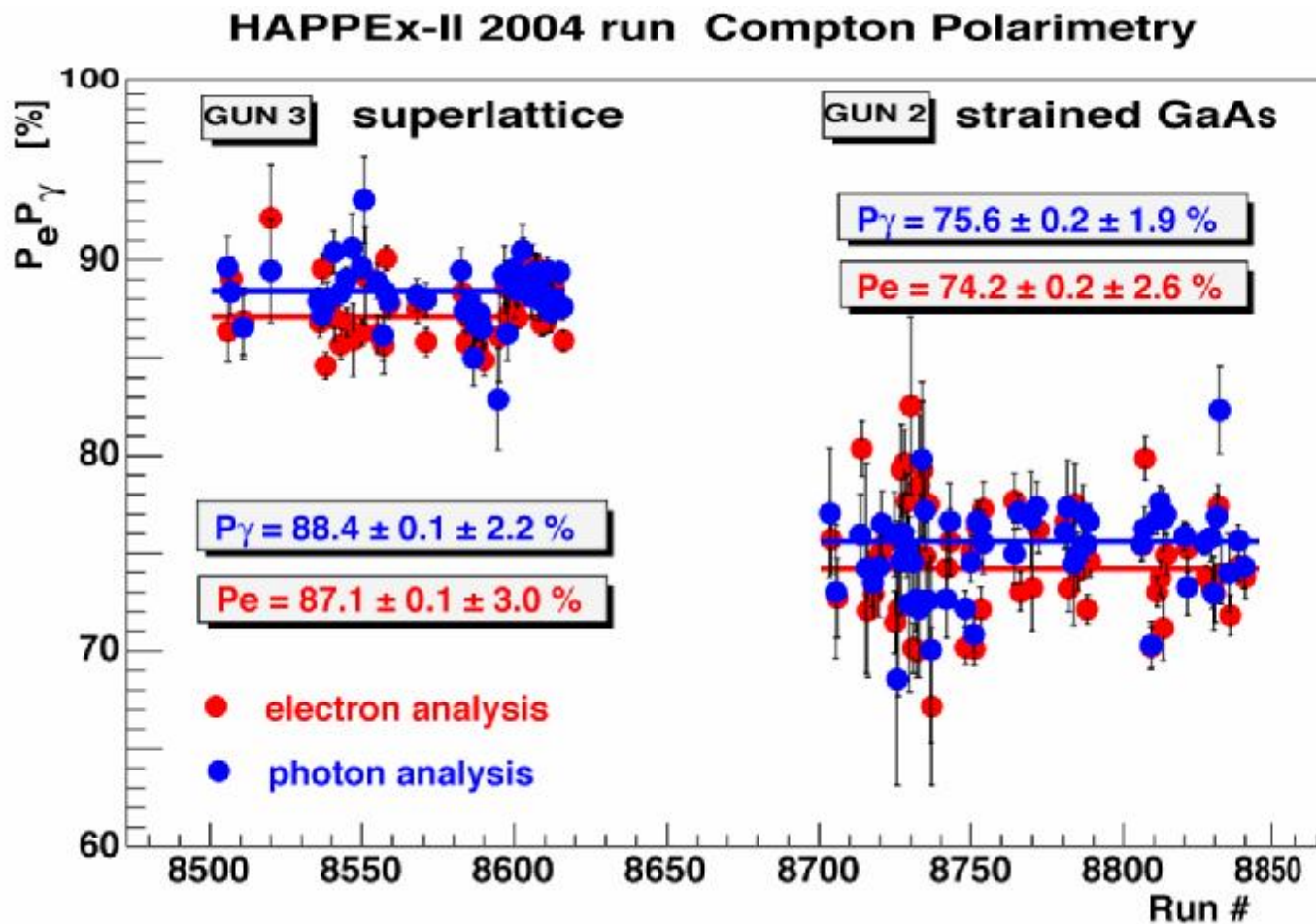


No strain relaxation
QE ~ 1.0 %
Pol ~ 85%
@ 780 nm

$$\text{FOM} \propto \mu I P^2$$



And, it really works!



Experiment
Figure of
Merit

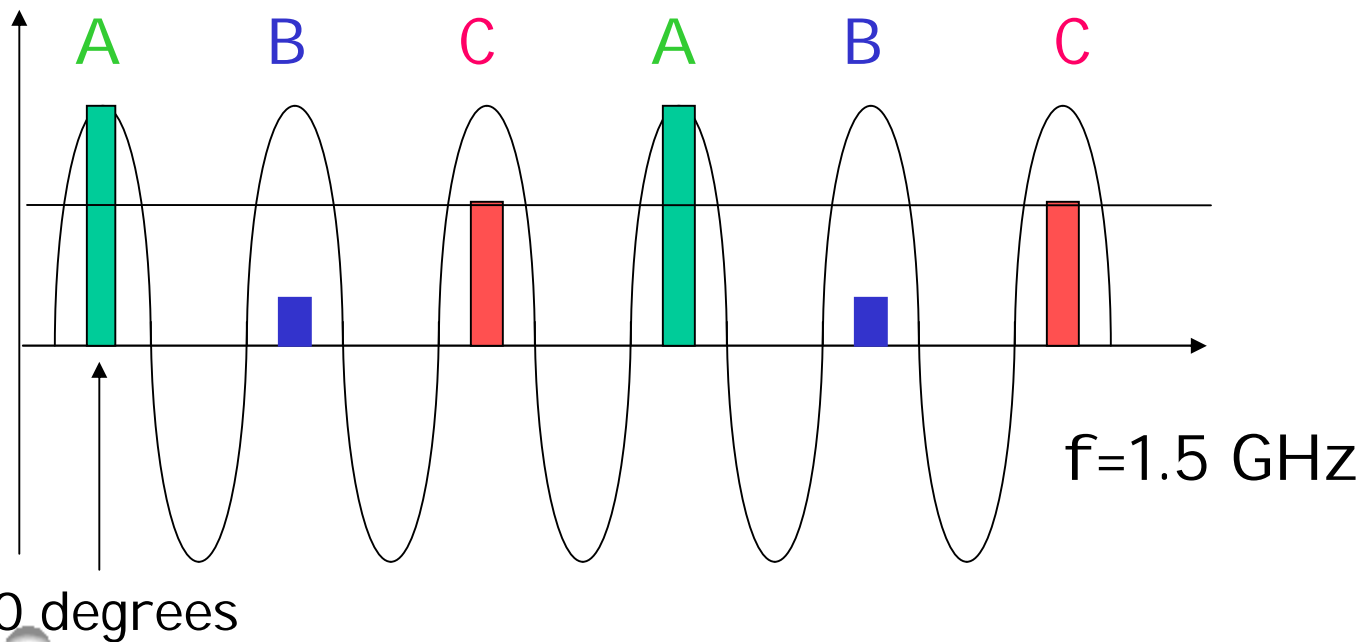
$$\frac{P_{\text{sup.}}^2 I}{P_{\text{str.}}^2 I} = 1.38$$



CEBAF Overview

CEBAF Benefits;

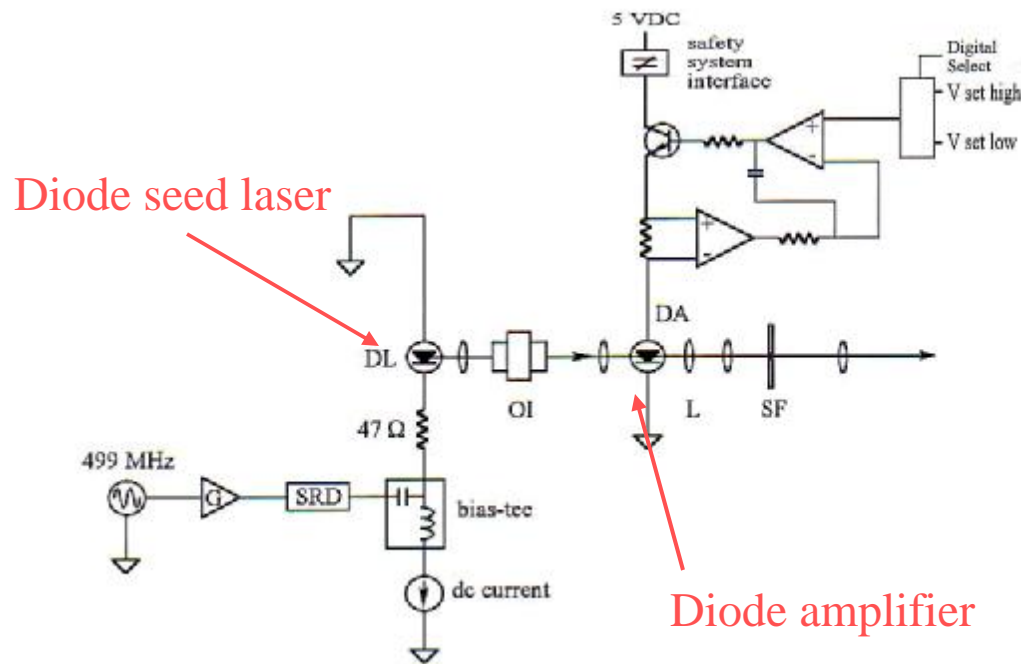
- Ø Recirculating LINACs
- Ø Superconducting Cavities
- Ø Three Halls = 3x the physics



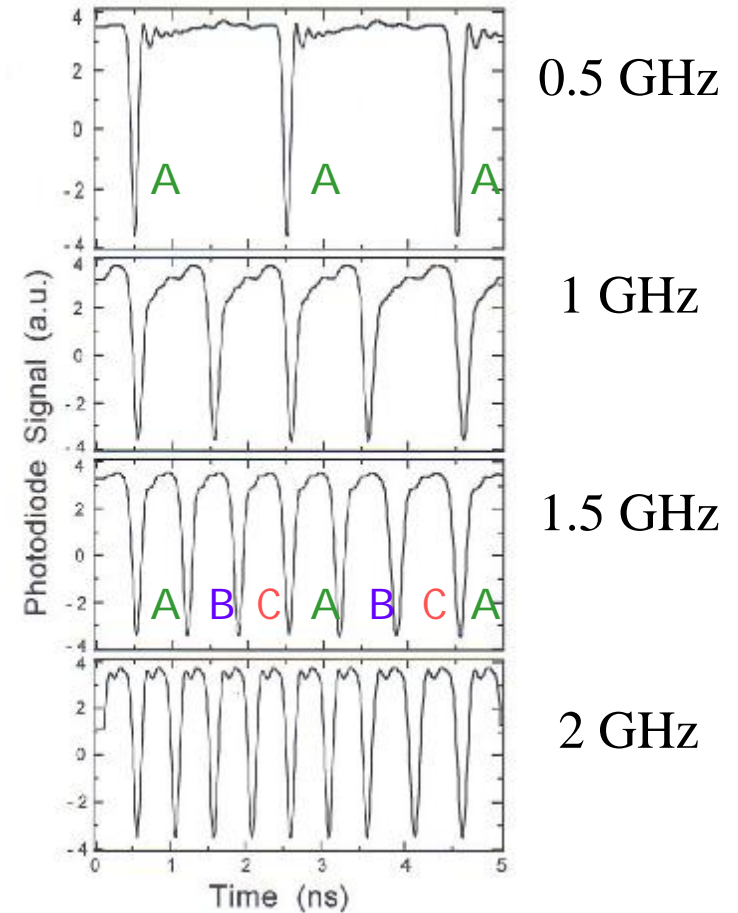
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Radio Frequency Pulsed Lasers

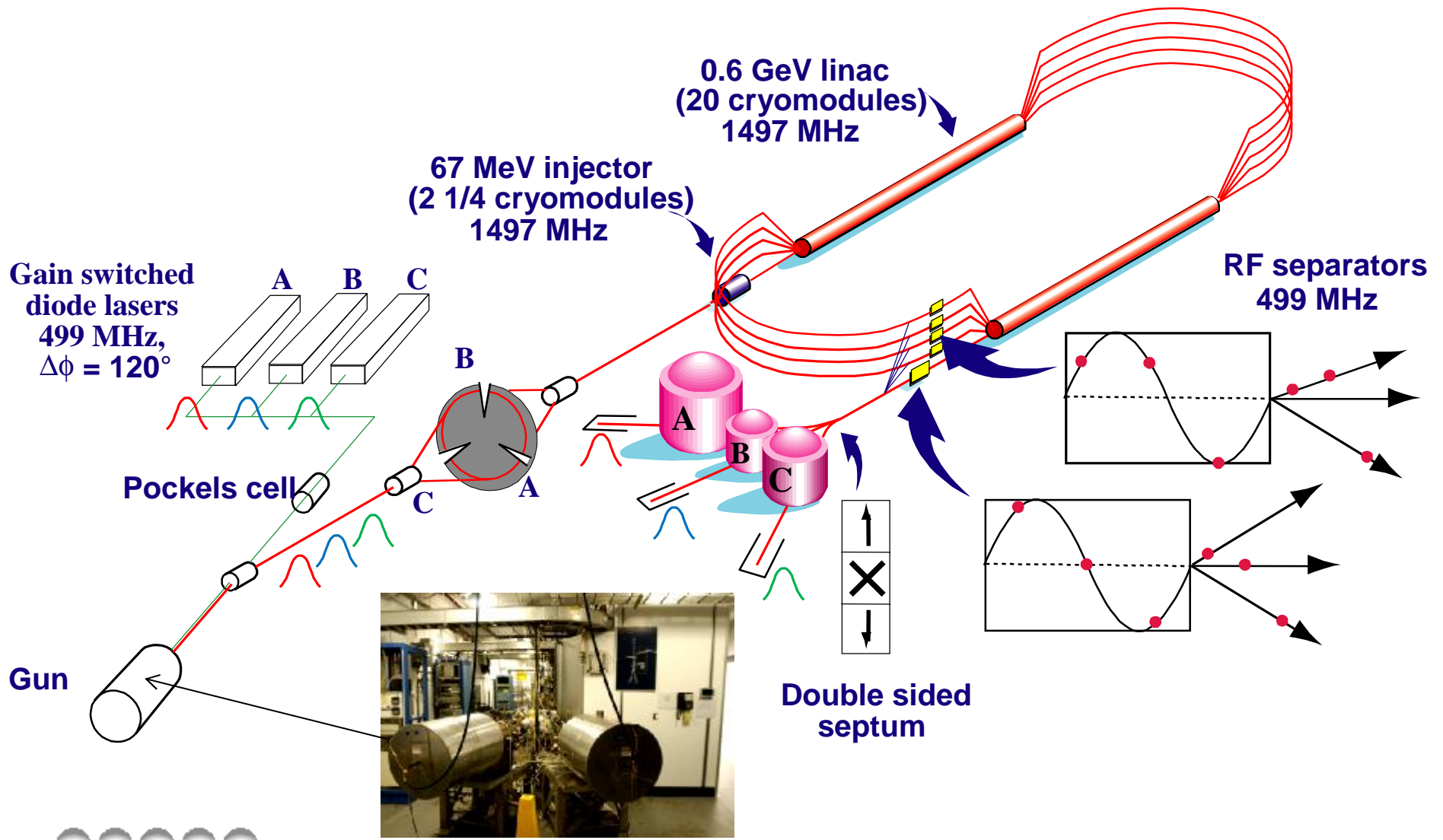
RF Gain Switching



M. Poelker, Appl. Phys. Lett. **67**, 2762 (1995).

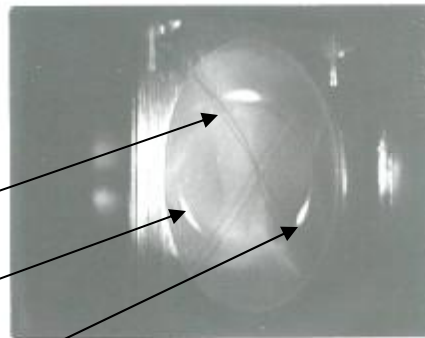
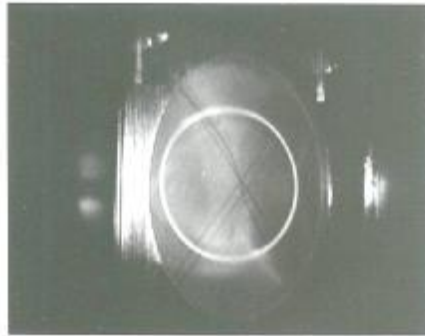


Continuous Electron Beam Accelerator Facility



Synchronous Photoinjection

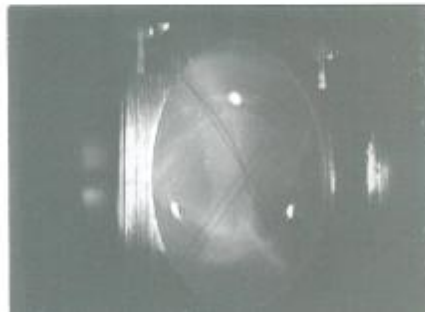
Chopper
viewer for
three beams;



Beam to Hall B

Beam to Hall A

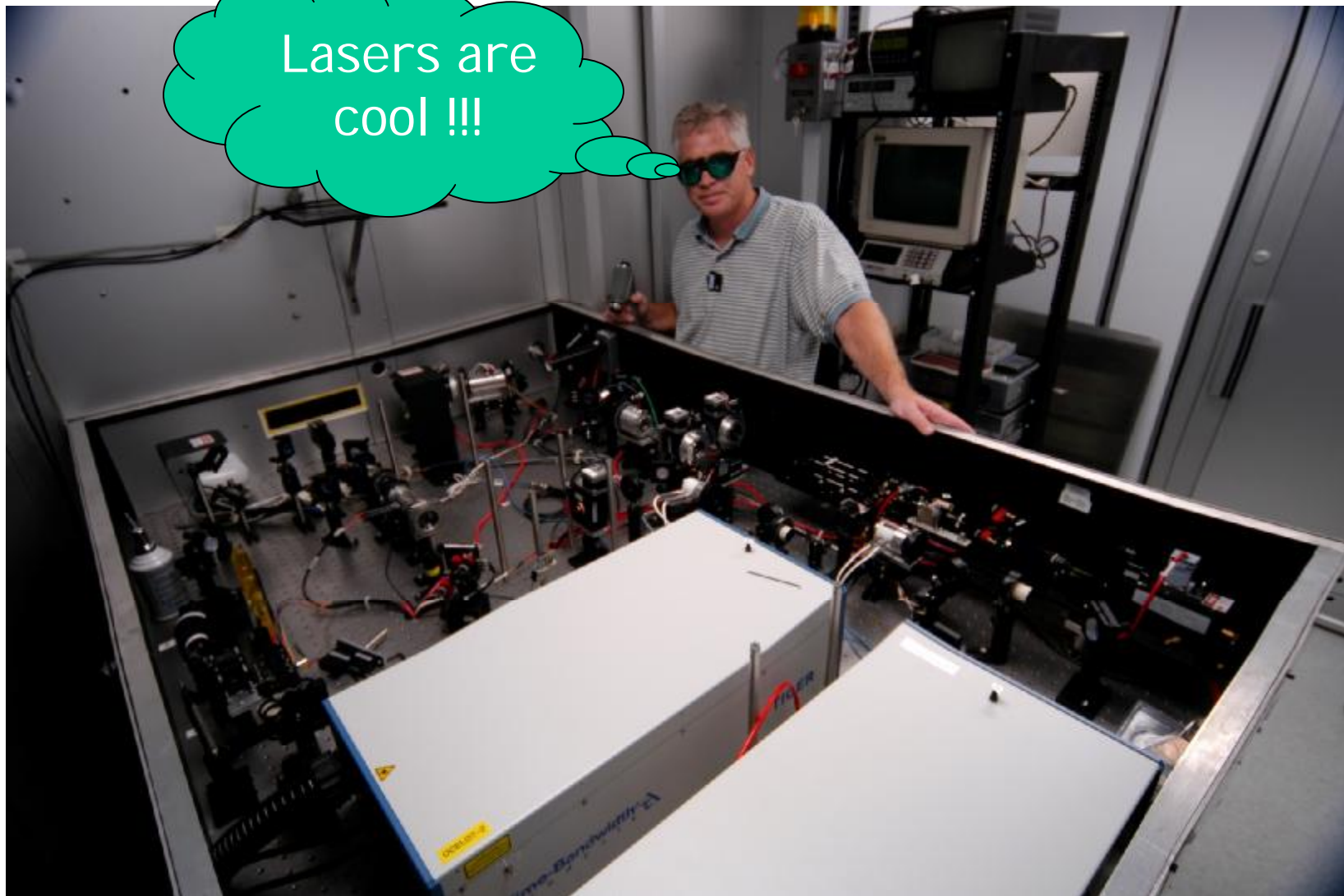
Beam to Hall C



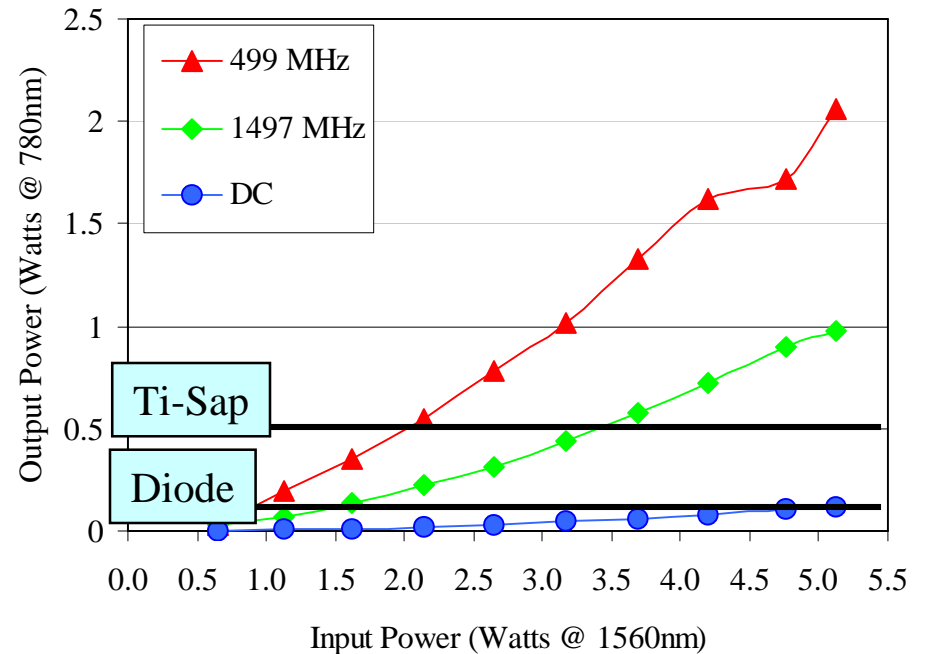
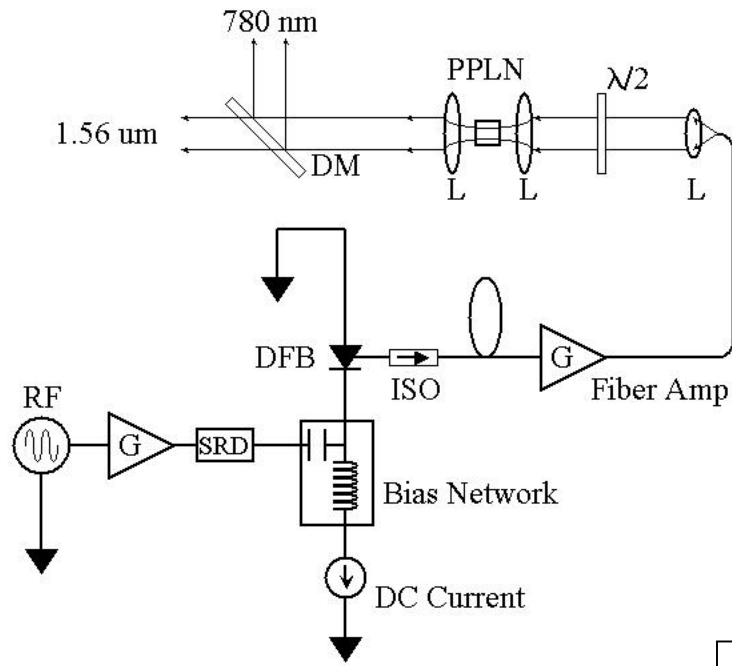
- DC Laser
(wasted electrons)
- Pulsed laser
(much better)
- PreBuncher
(even better)



Laser Room for Dust & Climate Control



New Fiber-Based Drive Laser



J. Hansknecht and M. Poelker, Phys. Rev. ST Accel. Beams 9, 063501 (2006)

- Ø Gain-switching better than modelocking; no phase lock problems
- Ø Very high power
- Ø Telecom industry spurs growth, ensures availability
- Ø Useful because of superlattice photocathode (requires 780nm)

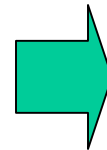


New fiber technology-based laser system

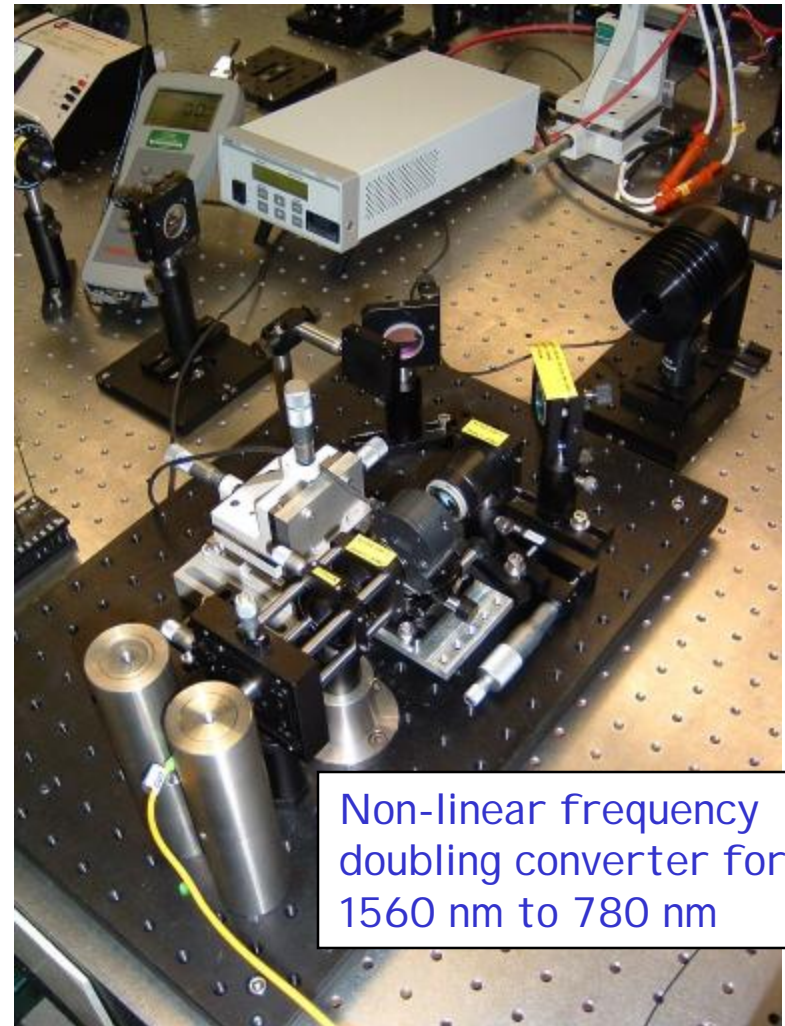
RF locked low-power
1560 nm fiber diode



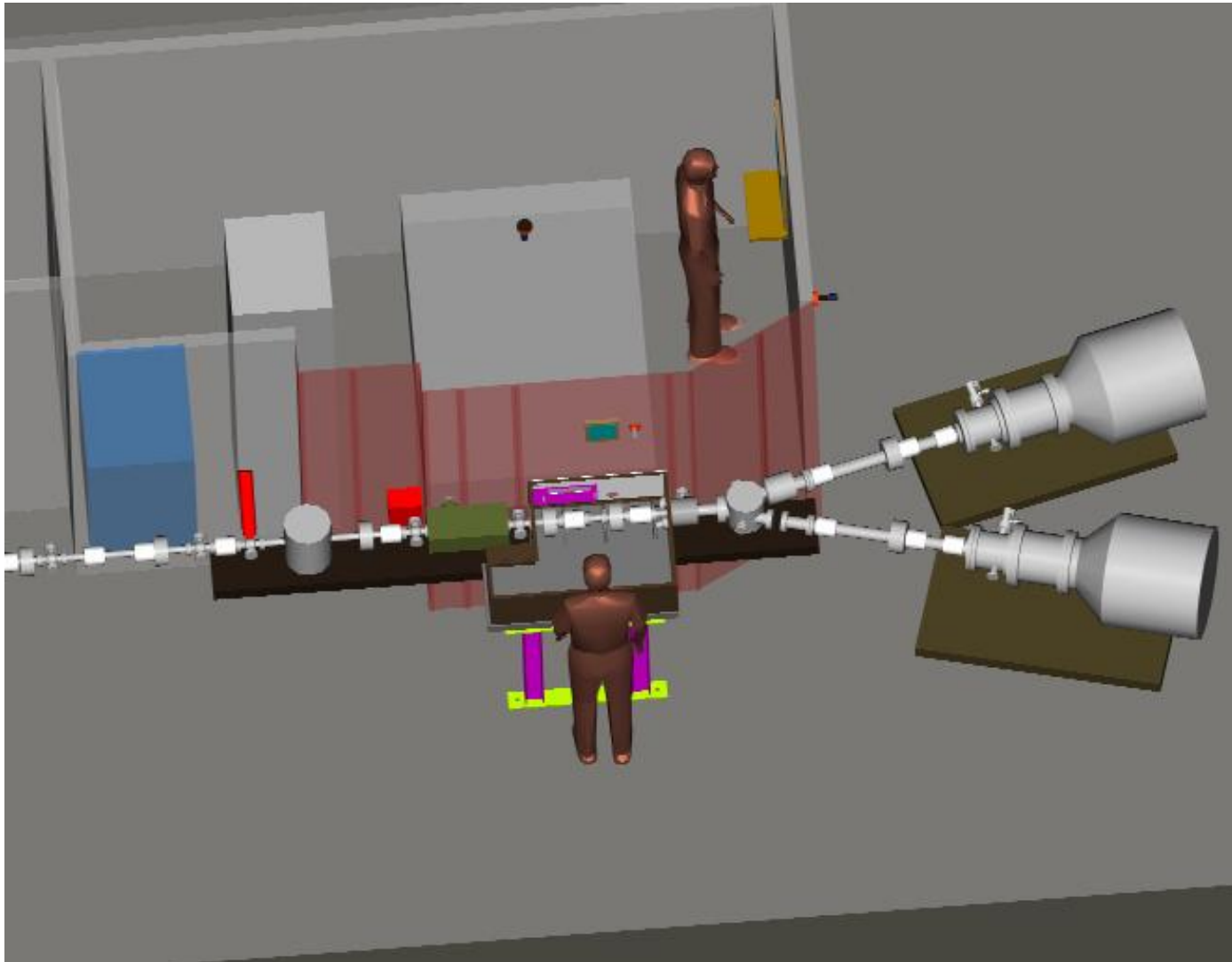
High power 1560 nm
fiber amplifier



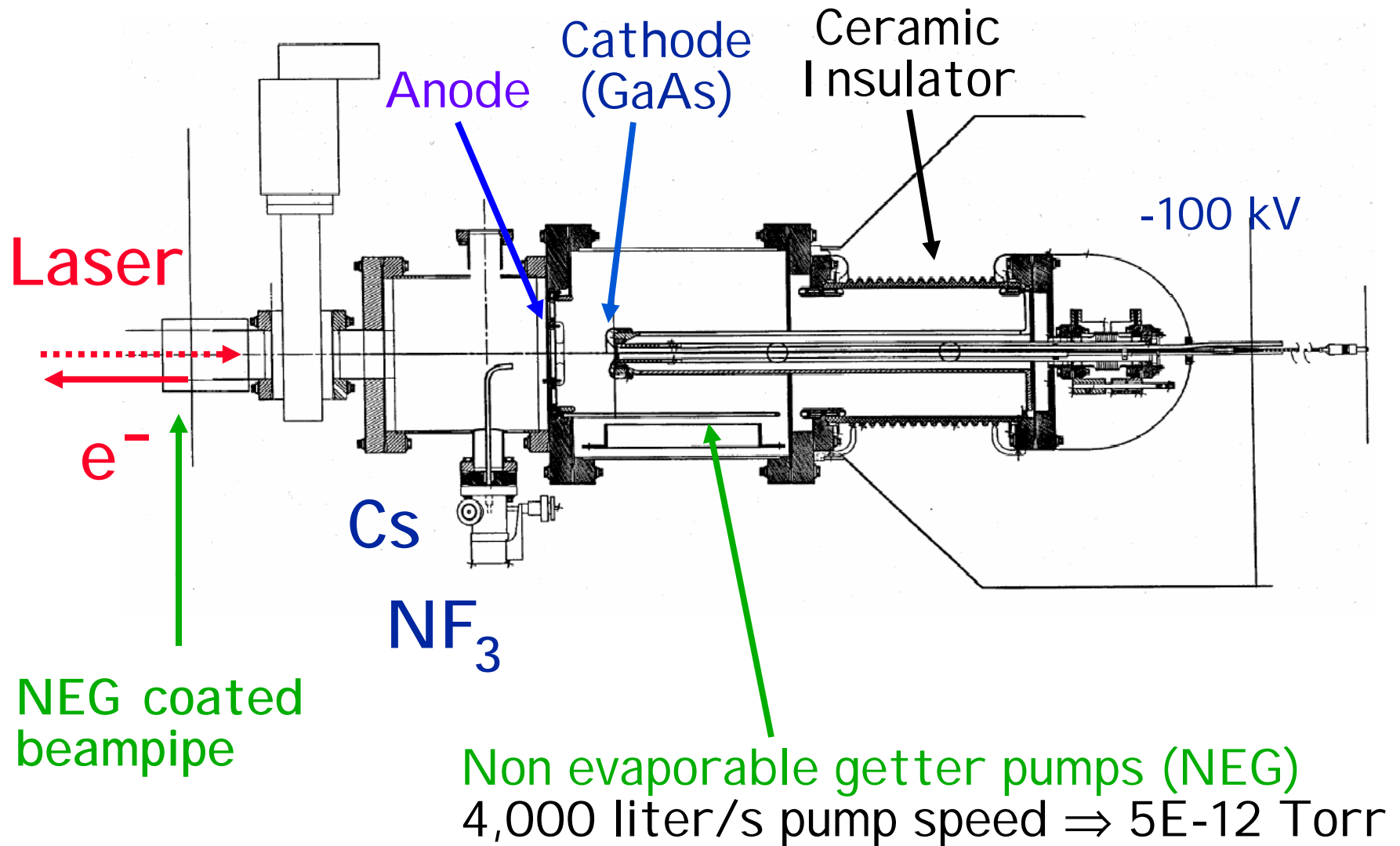
Non-linear frequency
doubling converter for
1560 nm to 780 nm



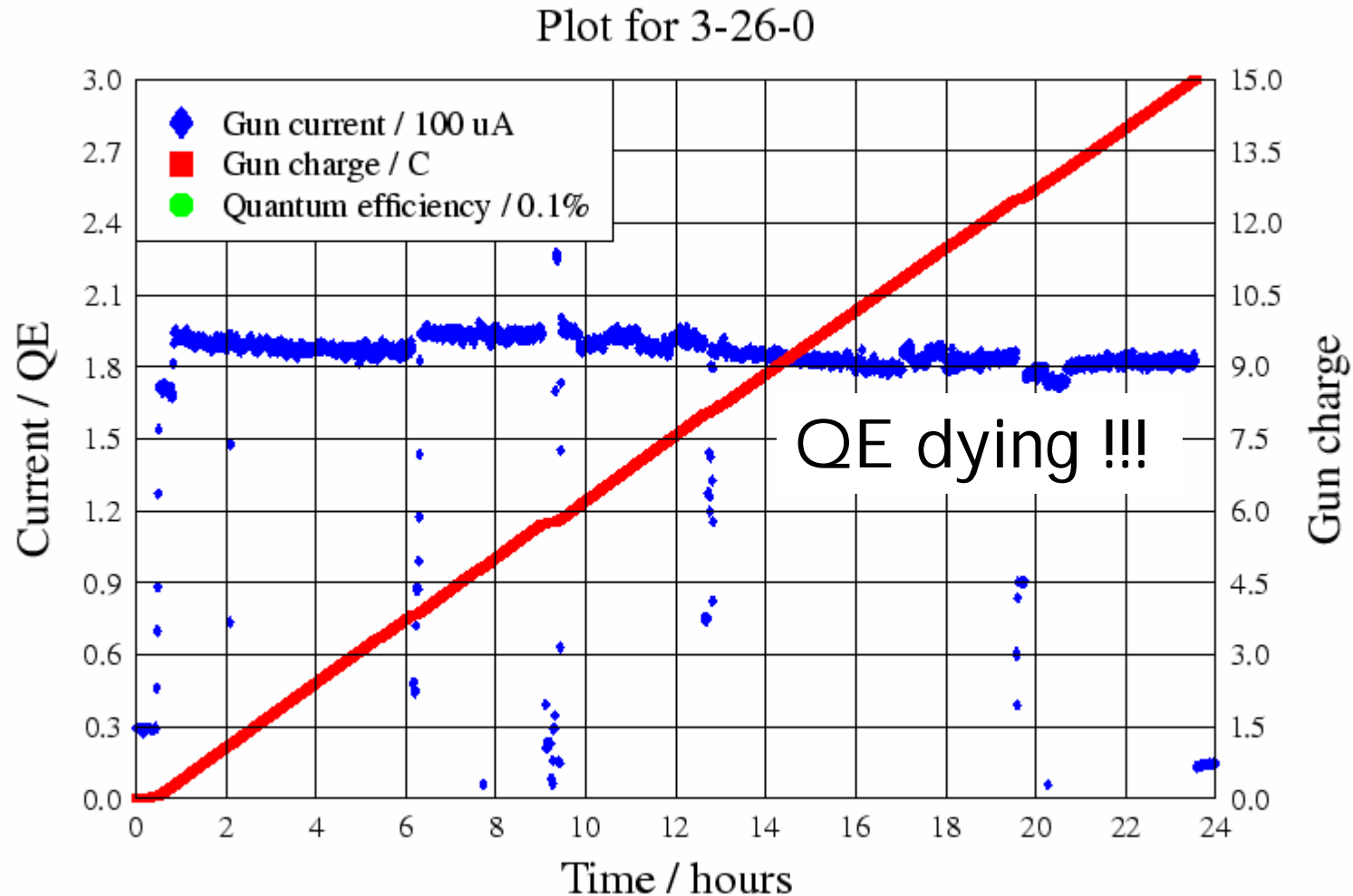
"100 keV" Photoinjector



JLab vent/bake polarized source...



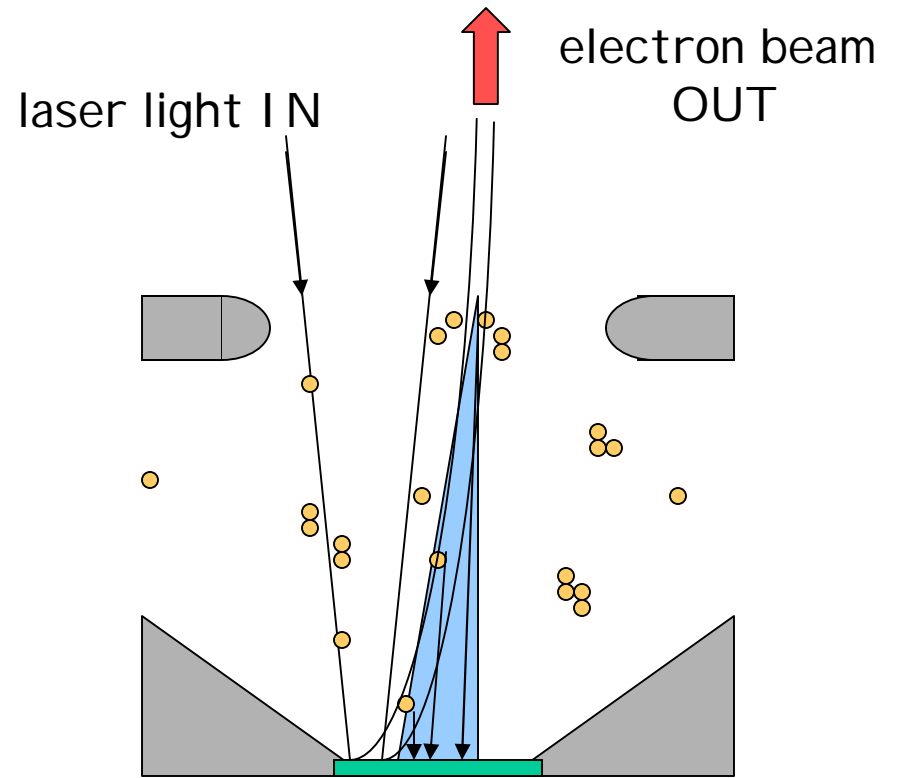
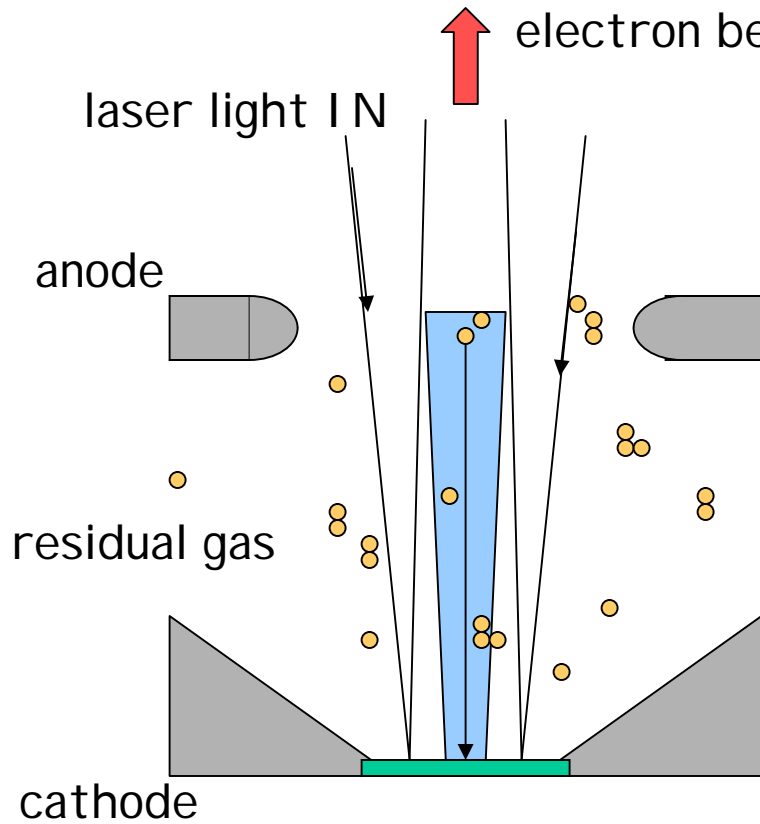
Who wants polarized electrons?



I on Back-Bombardment

High energy ions focused to electrostatic center

We don't run beam from electrostatic center

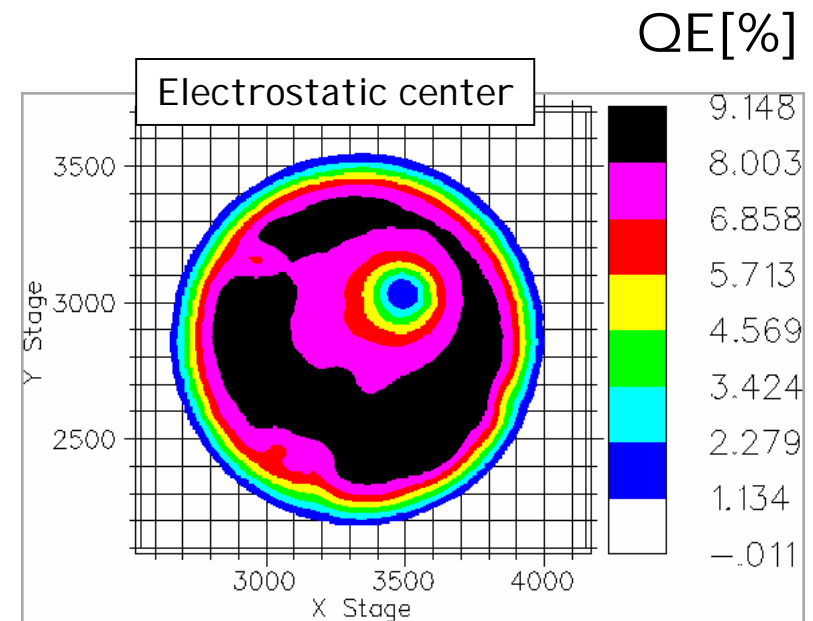
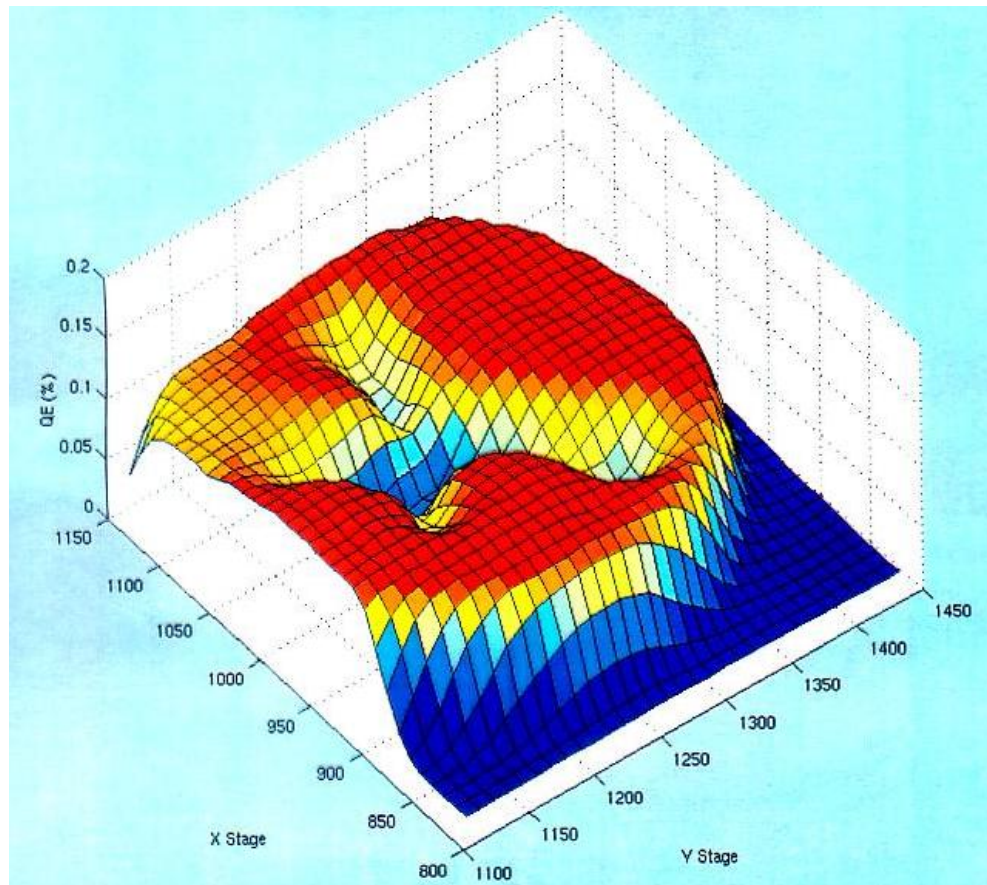


Ions create QE trough to electrostatic center

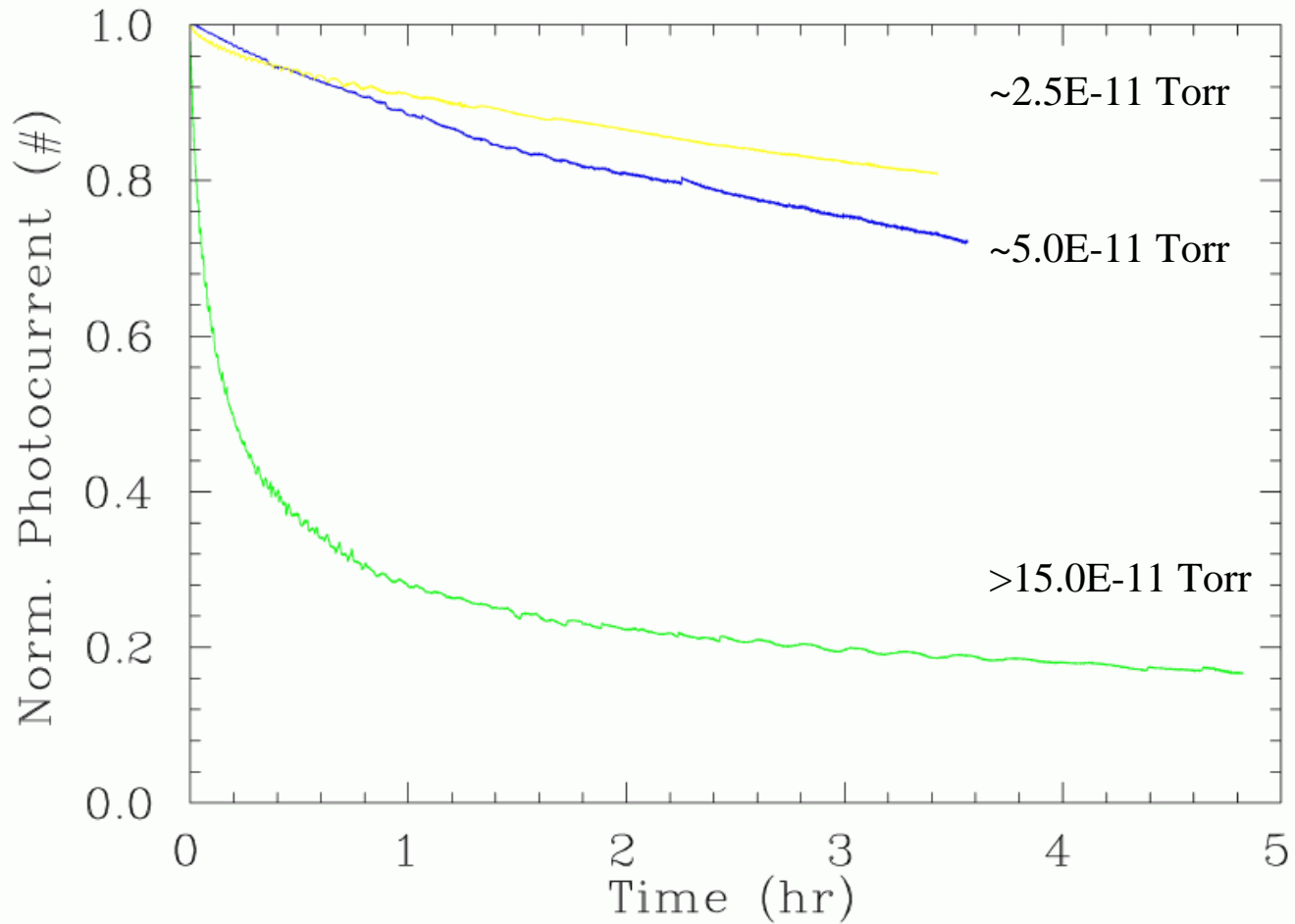


Bad, bad ions...

Imperfect vacuum => QE degrades via ion backbombardment



Better Vacuum = Longer Lifetime



↑
Better
Vacuum



We understand Alice's worry...



The woods were dark and foreboding, and Alice sensed that sinister eyes were watching her every step. Worst of all, she knew that Nature abhorred a vacuum.

“The woods were dark and foreboding, and Alice sensed that sinister eyes were watching her every step. Worst of all, she knew that Nature abhorred a vacuum” – Gary Larson

Vacuum Conditions at CEBAF

Application	Pressure Range	Location	Vacuum Regime
Beamline to dumps	10^{-5} Torr	Target to dump line	Medium
Insulating vacuum for cryogens	10^{-4} Torr to 10^{-7} Torr	Cryomodules, transfer lines	Medium to high
Targets, Scattering Chambers	10^{-6} to 10^{-7} Torr	Experimental Halls	High to very high
RF waveguide warm to cold windows	10^{-7} to 10^{-9} Torr	Between warm and cold RF windows	High to very high
Warm beamline vacuum	10^{-7} to 10^{-8} Torr or better	Arcs, Hall beamline, BSY, some injector	High to very high
Warm region girders	10^{-9} Torr or better	Girders adjacent to cryomodules	Very high to ultrahigh
Differential pumps	Below 10^{-10} Torr	Ends of linacs, injector cryomodules and guns	Ultrahigh vacuum
Baked beamline	10^{-10} to 10^{-11} Torr	Y chamber, Wien filter, Pcup	Ultra high vacuum
Polarized guns	10^{-11} to 10^{-12} Torr	Inside Polarized guns	Ultra/Extreme high vacuum
SRF cavity vacuum	$< 10^{-12}$ Torr	Inside SRF cavities with walls at 2K	Extreme high vacuum



Vacuum regimes

- Low, Medium Vacuum ($>10^{-3}$ Torr)
 - Viscous flow
 - interactions between particles are significant
 - Mean free path less than 1 mm
 - High, Very High Vacuum (10^{-3} to 10^{-9} Torr)
 - Transition region
 - Ultra High Vacuum (10^{-9} - 10^{-12} Torr)
 - Molecular flow
 - interactions between particles are negligible
 - interactions primarily with chamber walls
 - Mean free path 100-10,000 km
 - Extreme High ($<10^{-12}$ Torr)
 - Molecular flow
 - Mean free path 100,000 km or greater
- $\text{Air} \sim 10^{16} / \text{Torr-cm}^3$



Where does the gas come from?

- **Outgassing from the system**
 - Metal and non-metal (viton o-rings, ceramics) all outgas
 - Primarily water in unbaked systems
 - Primarily hydrogen from steel in baked systems
- **Leaks**
 - Real
 - Gaskets not sealed
 - Cracks in welds, bellows, ceramics, window joints
 - Superleaks that only open at very low temperatures
 - Virtual
 - Small volumes of gas trapped inside system (screw threads, etc.) that pump out slowly over time
- **Gas load caused by the beam**
 - Desorption of gases by elevated temperatures, electrons or photons striking surfaces, etc.
- **Engineered Loads** (targets, etc.) where gas is added
- **Permeation of gasses through materials**
 - Viton gaskets worse than metal seals
 - Hydrogen can permeate through stainless steel!



Ultra High Vacuum Pumps

- **Getter Pumps**

- Chemically active surface
 - Titanium sublimed from hot filament
 - Non-Evaporative Getters
- Molecules stick when they hit
 - Does not work well for inert gasses such as Argon, Helium or for methane

- **Ion Pumps**

- Electric field to ionize gasses
- Magnetic field to direct gasses into cathodes where they are trapped
 - Has some pumping capability for noble gasses

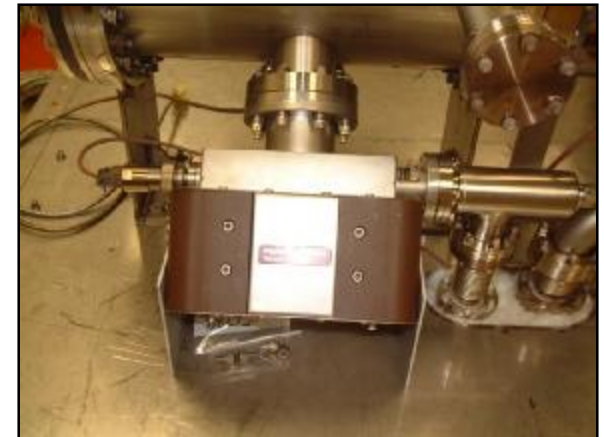
- **Baking used to get pressures below 10^{-10} Torr**

- 250°C for 30 hours removes water vapor bonded to surface that otherwise limits pressure

- Avoid contamination by oils due to roughing pumps, fingerprints, machining residue.



NEG pump array

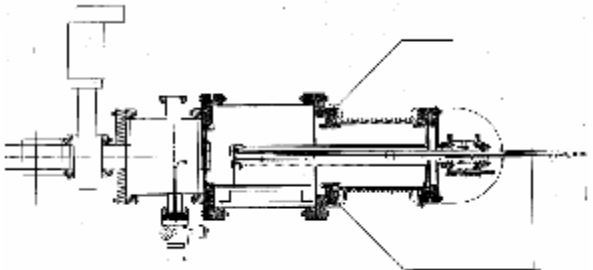
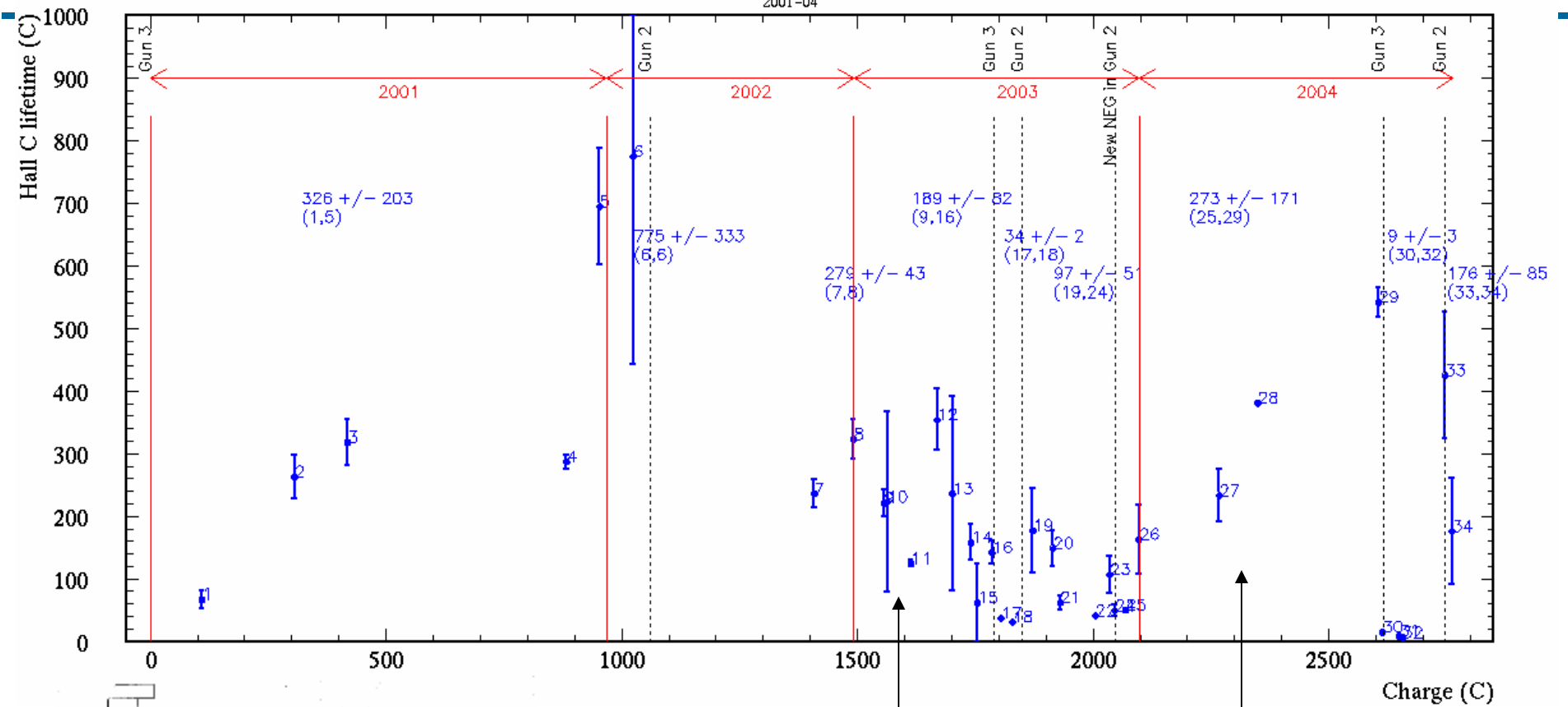


Ion Pump



CEBAF Gun Charge Lifetime (2001-2004)

Data compiled by M. Baylac

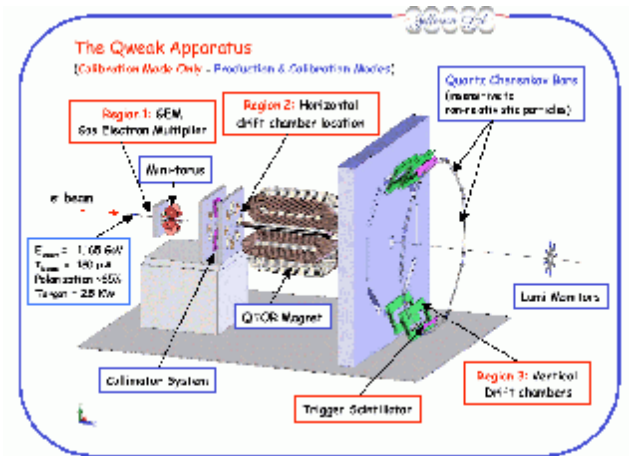
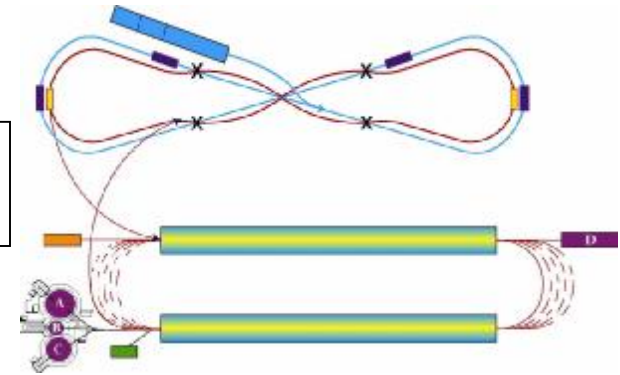
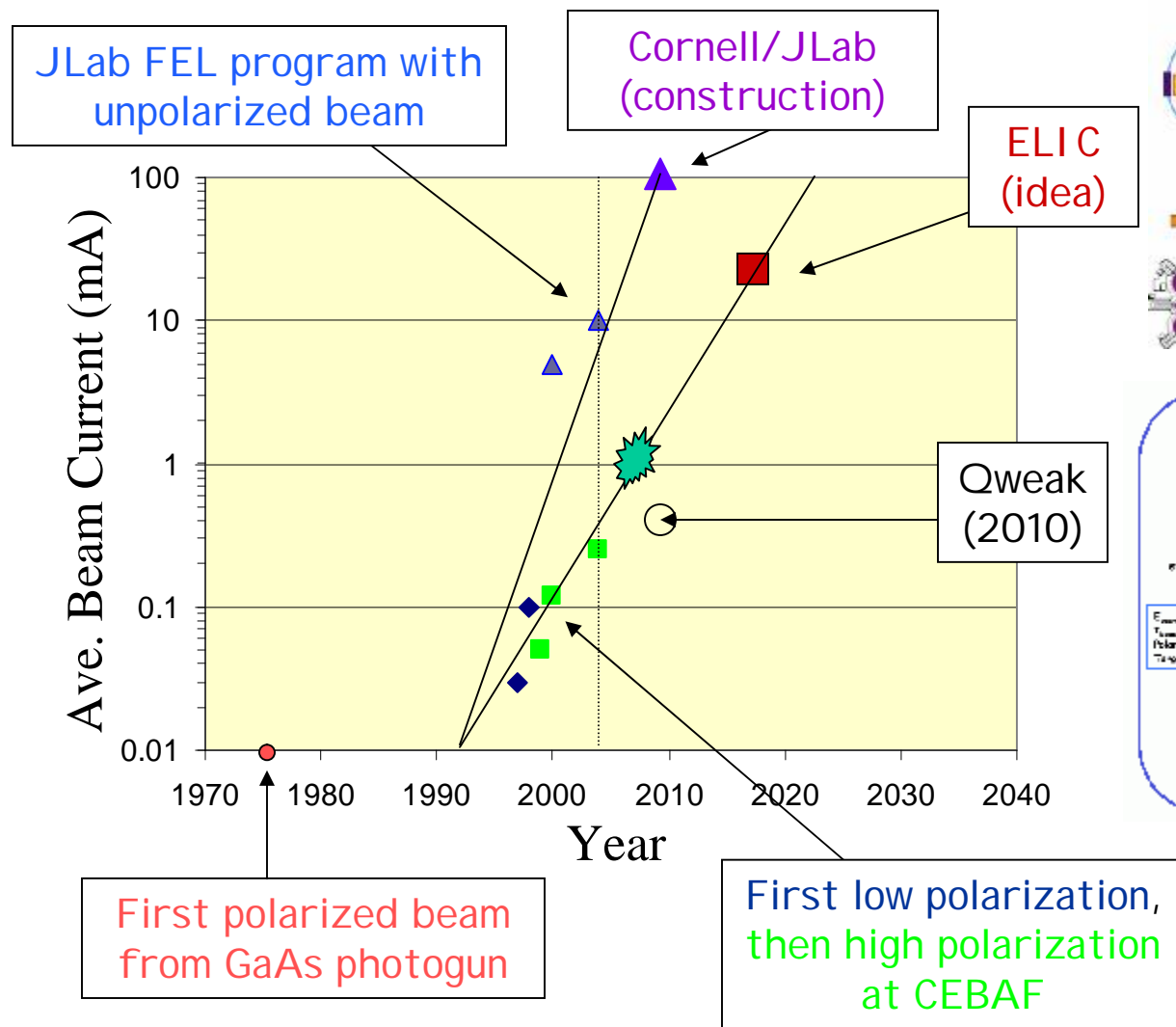


Charge Lifetime
Steadily Decreasing

NEG replacement
Summer 2003
improves lifetime



GaAs Trending Higher Average Current



CEBAF Photoinjector



1997



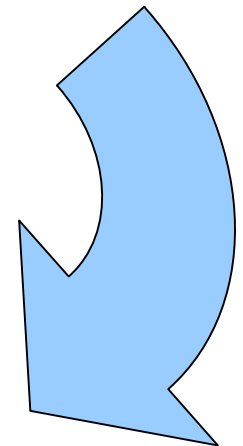
1998



1999-2007

Long photocathode lifetime:

- Gun & Beamlines "NEG's" => Good Vacuum
- No short focal length elements
- Photocathodes with anodized edge
- Synchronous photoinjection
- (Spare Gun)



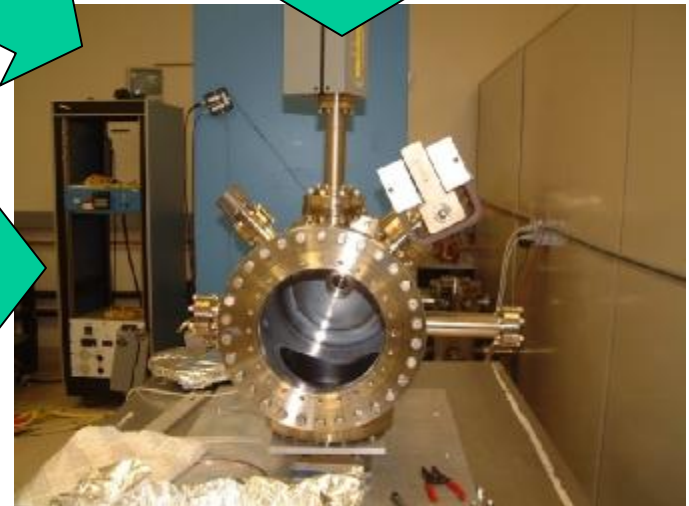
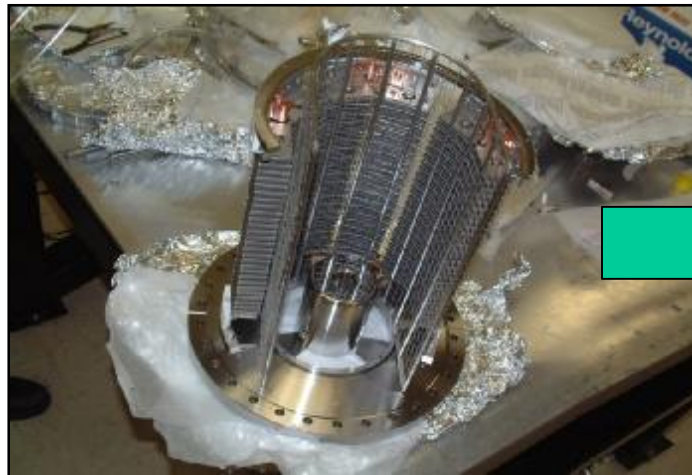
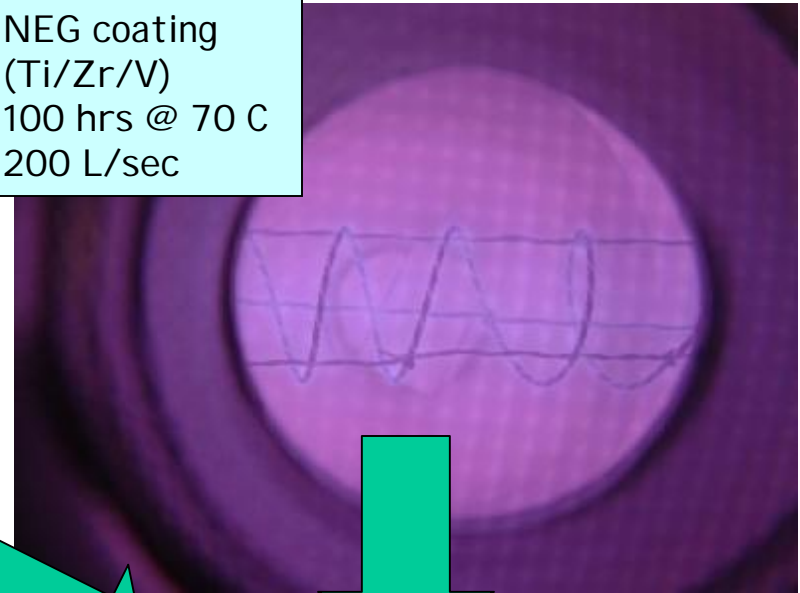
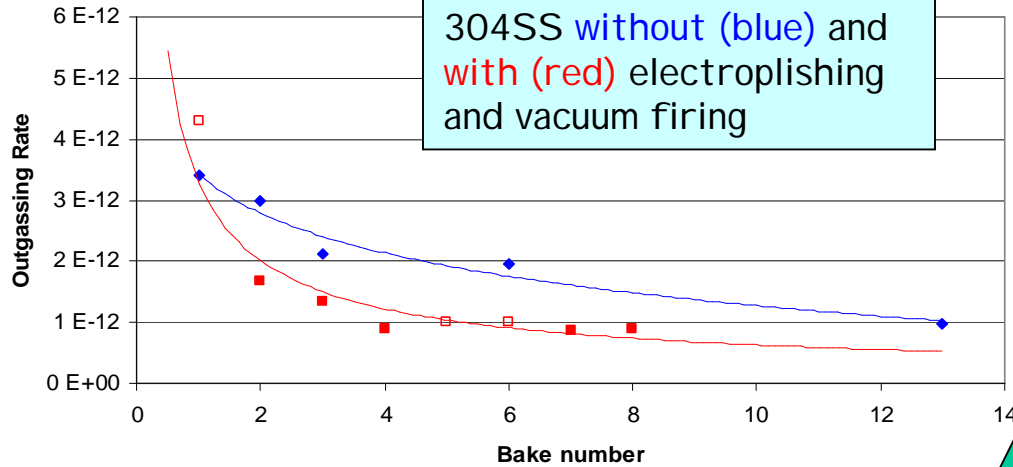
What now ... ???



Improvements to the High Voltage Chamber Vacuum

304 SS: Electropolished & Vacuum Fired
(AVS: 3 hrs @ 900 C @ 3×10^{-6} T)

NEG coating
(Ti/Zr/V)
100 hrs @ 70 C
200 L/sec



New Load Lock Gun in Test Stand Spring '06

Heat/activation chamber

Goal: 8 hours swap photocathode
Present: ~12 hours

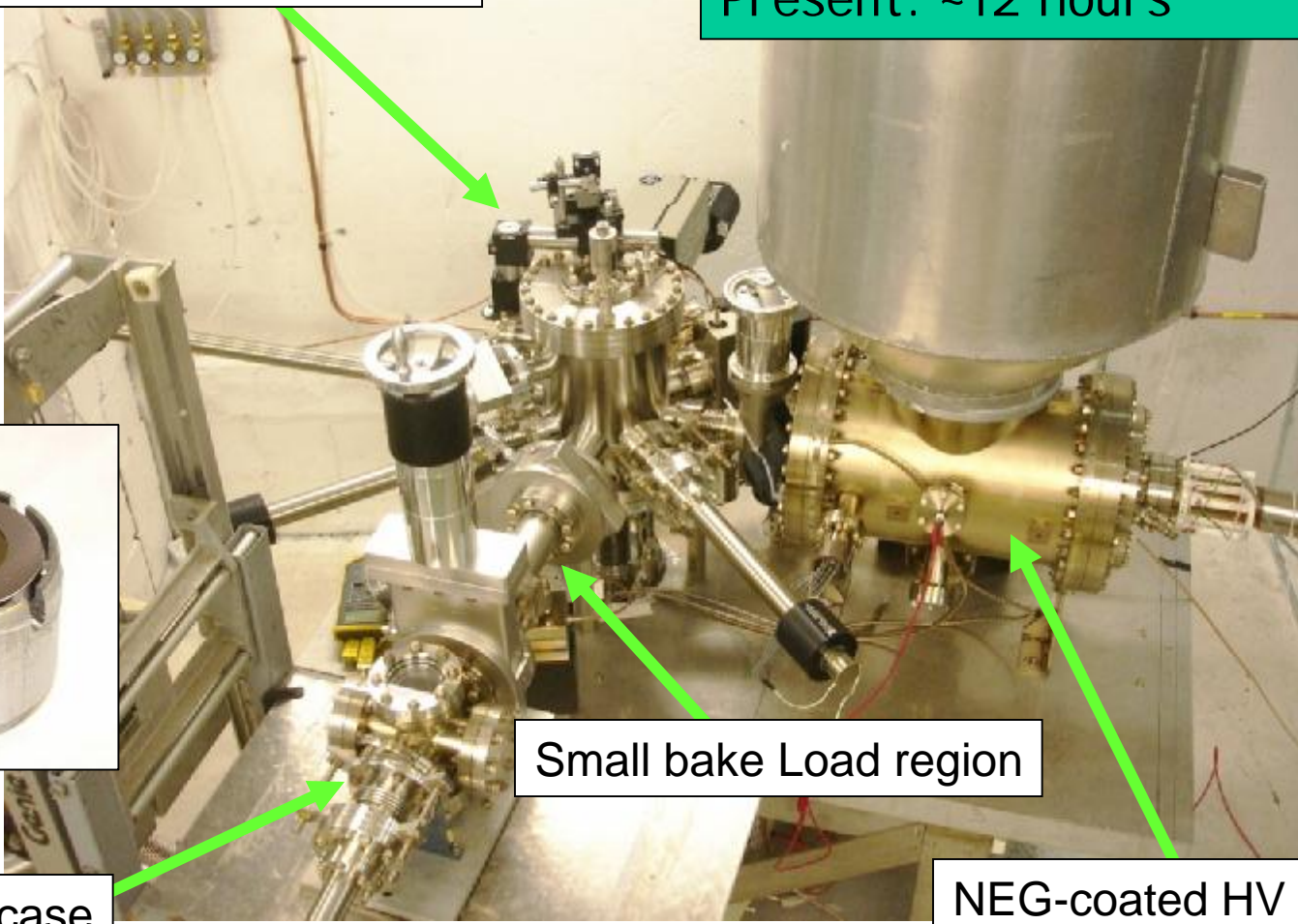
x4



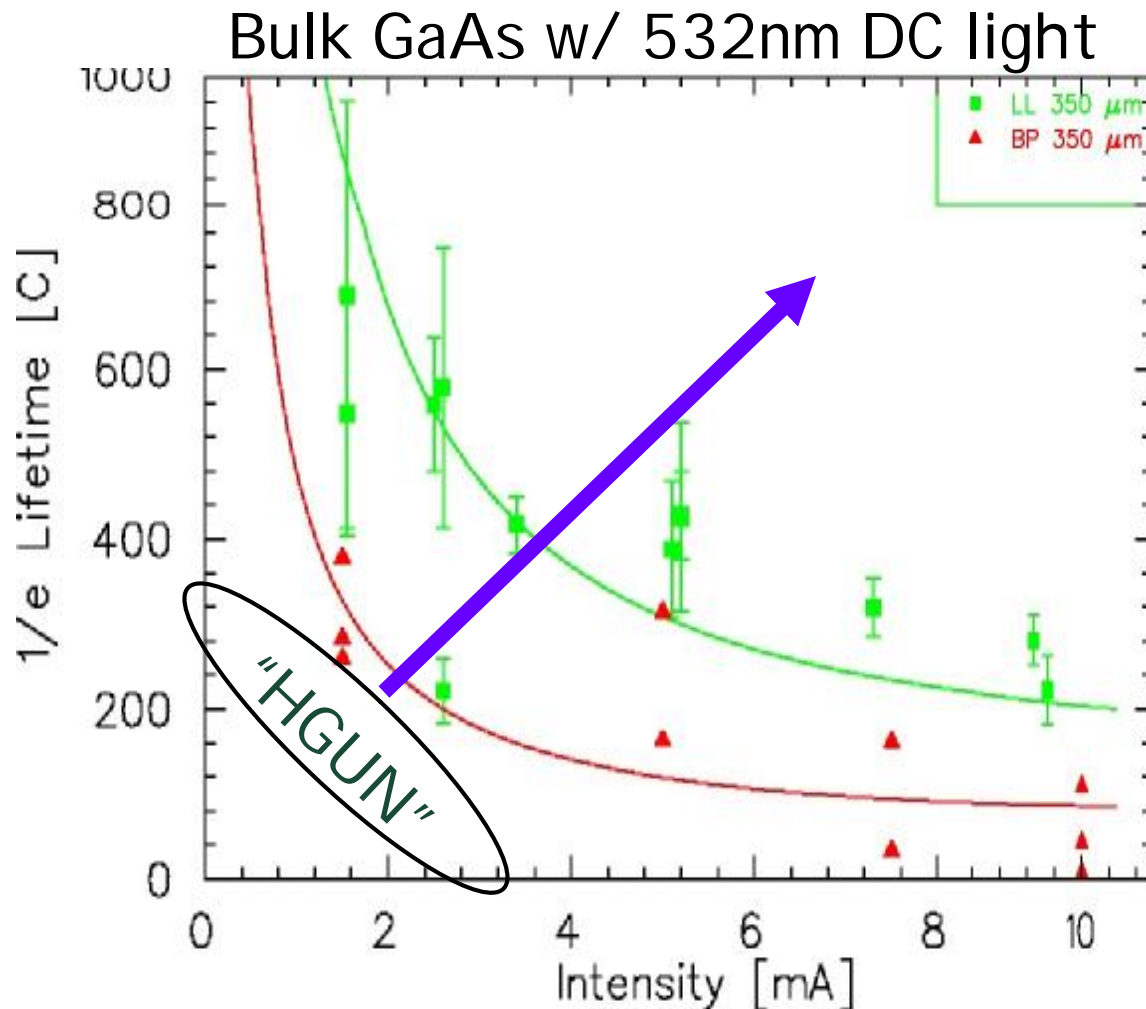
Suitcase

Small bake Load region

NEG-coated HV chamber



CEBAF e- source: current & lifetime



Improve vacuum

- Reduce surface area
- 400 C bake
- Ion pump = Gas Source?

Limit "bad" electrons

- Eliminate FE
- Laser handling

Increase QE

- Longer heat clean
- Better vacuum

High-P Photocathode

J. Grames et al., in AIP Conference Proceedings 915, p. 1037-1044 (2006).



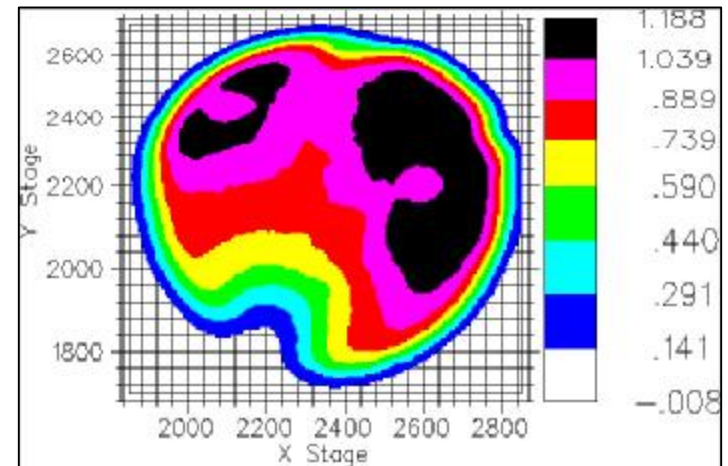
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1 milliAmp demo from High-P Photocathode*

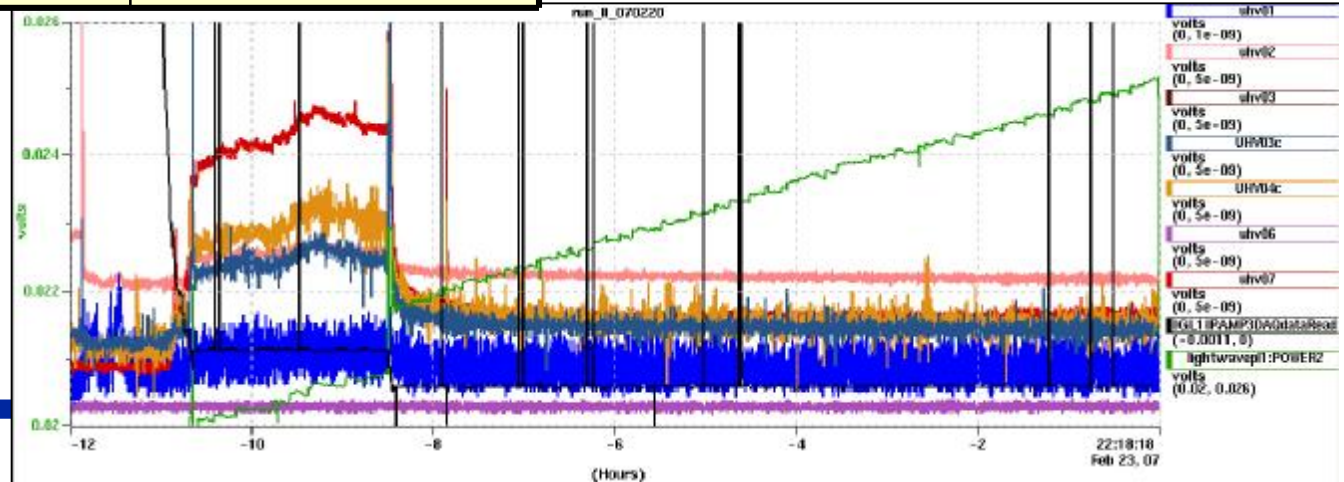
Parameter	Value
Laser Rep Rate (CW)	499 MHz
Laser Pulse Length	30 psec
Wavelength	780 nm
Laser Spot Size (FWHM)	450 μ m
Average Current	1 mA
Run Duration	8.25 hr
Extracted Charge	30.3 C
Charge Lifetime	210 C
Areal Charge Lifetime	160 kC/cm ²

* Note: did not measure polarization

High Initial QE [%]

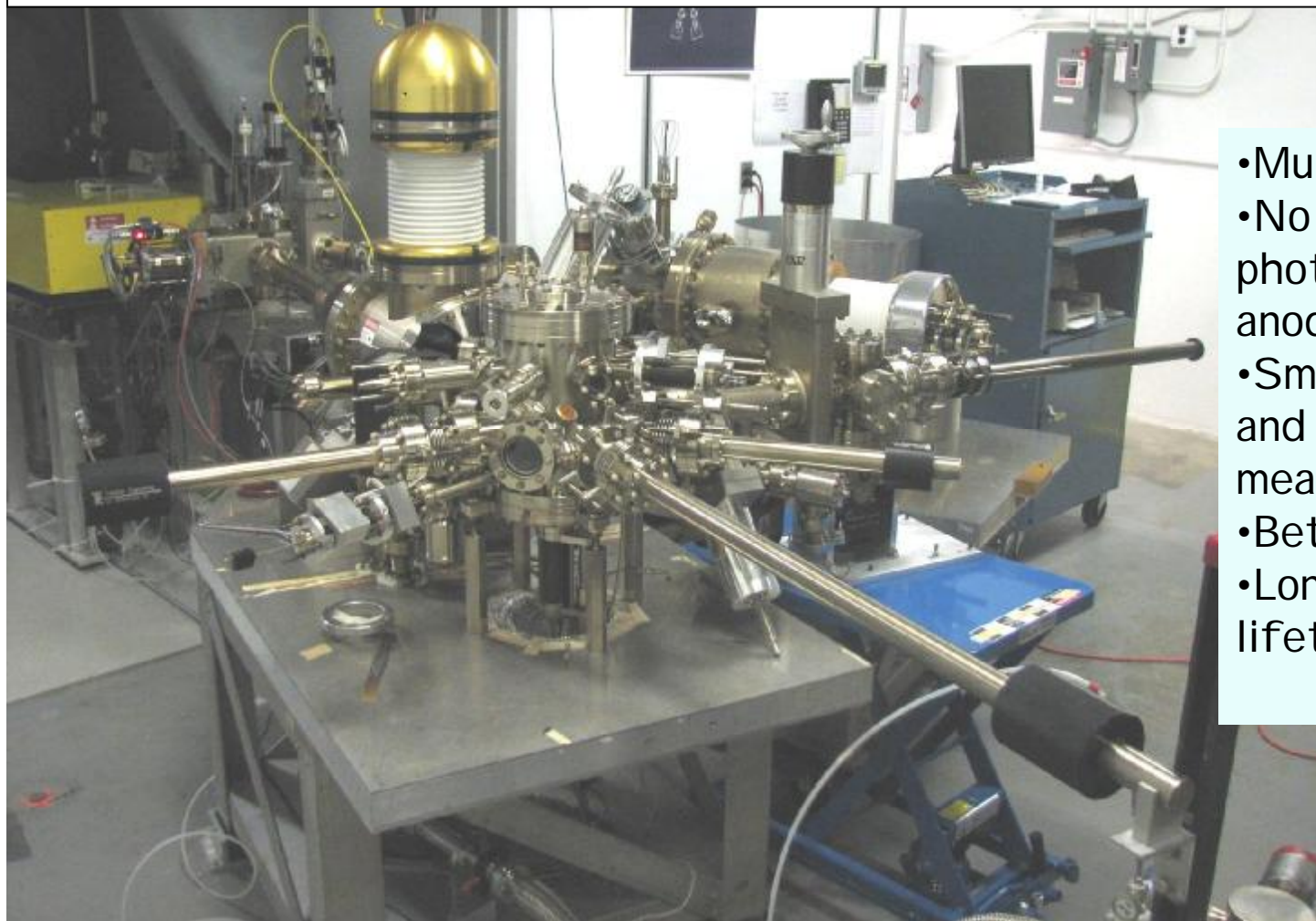


Vacuum signals
Laser Power
Beam Current



NEW CEBAF Load Locked Gun

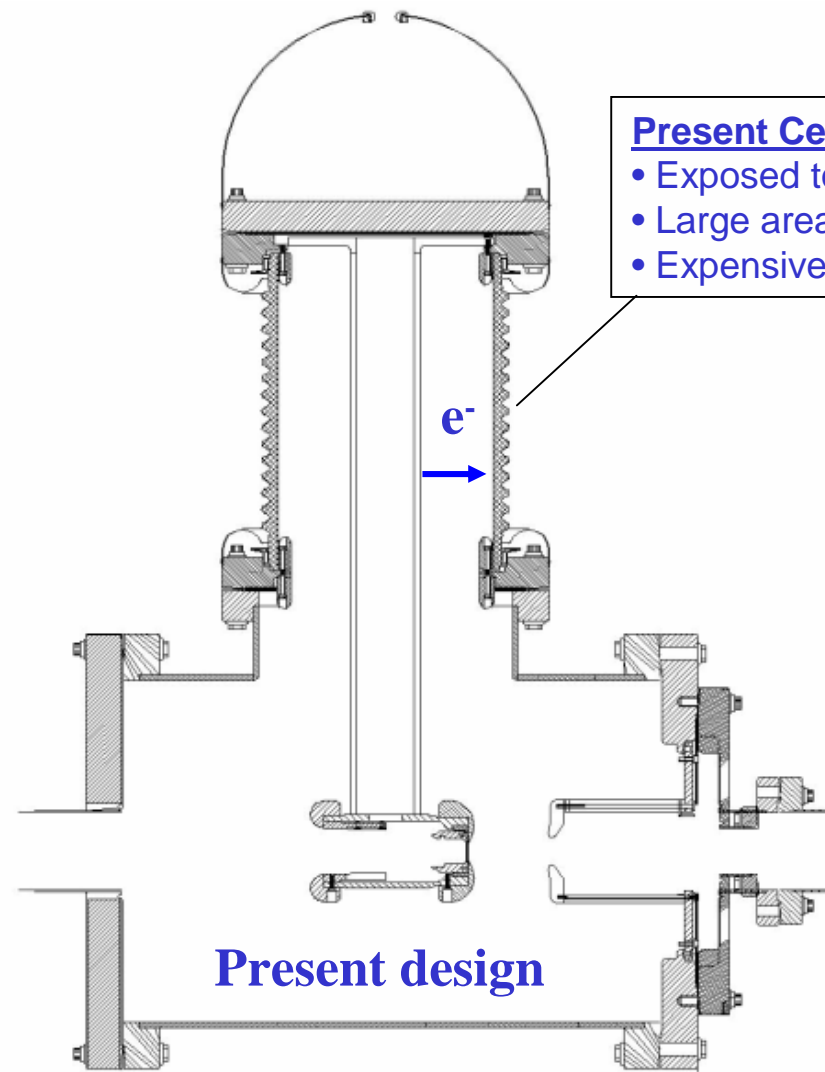
No more gun bakeouts! Photocathode replaced in 8 hours versus 4 days.



- Multiple samples,
- No more photocathode edge anodizing,
- Smaller surface area and no more venting means:
 - Better gun vacuum,
 - Longer photocathode lifetime



Build Higher Voltage Inverted Gun



Present Ceramic

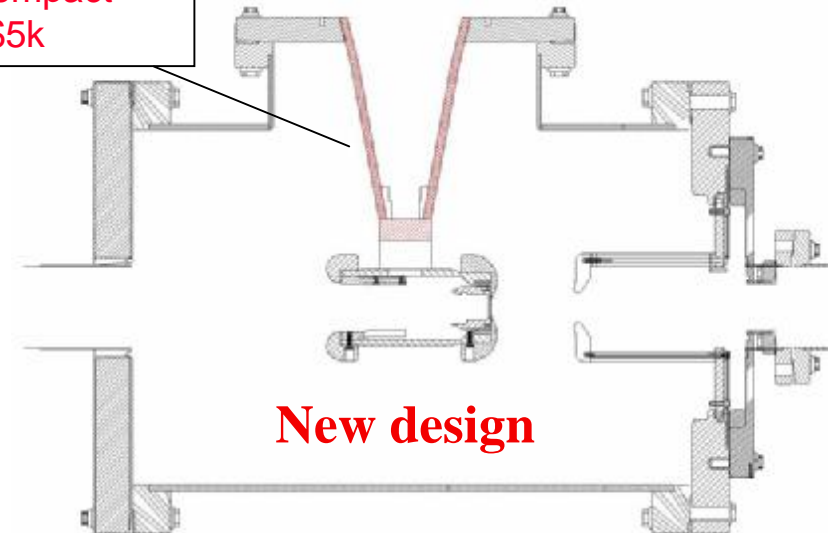
- Exposed to field emission
- Large area
- Expensive (~\$50k)

Medical x-ray
technology



New Ceramic

- Limited FE
- Compact
- ~\$5k

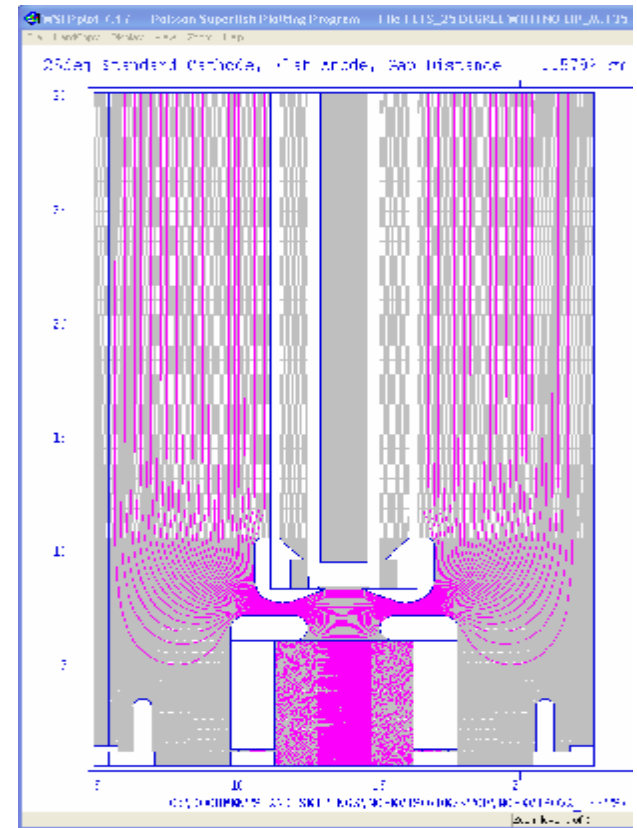
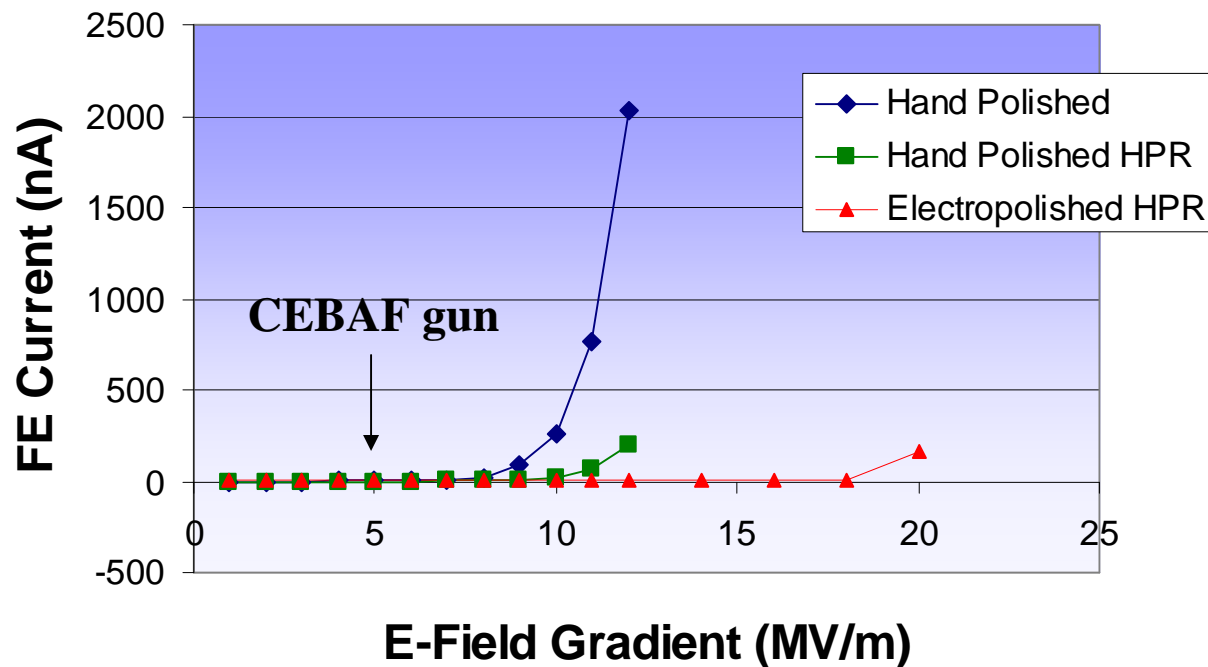


Eliminate Field Emission

Implement the SRF-cavity technique “high pressure rinsing”

Recent work of Maria Chevtsova, Ken Surles-Law with shaped electrodes

**FE from Handpolished 304 SS
Cathode Electrode with ~6 mm gap**



Ken is collaborating with SRF Institute to build single crystal Niobium electrodes.

